
3D VLSI: Next Generation 3D Integration Technology

QUALCOMM®

Karim Arabi
Vice President, R&D



Continued smartphone momentum

World's largest technology platform

~8B

Cumulative smartphone
unit shipments forecast
between 2014-2018



Mobile scale

Cumulative global unit shipments, 2013–2017

Smartphones
& Tablets



PCs

Vehicles

Digital media adapters

Digital video recorders

Portable game consoles

Portable media players

Audio systems

Blu-ray disc players

Digital cameras

Game consoles

Flat-panel TVs

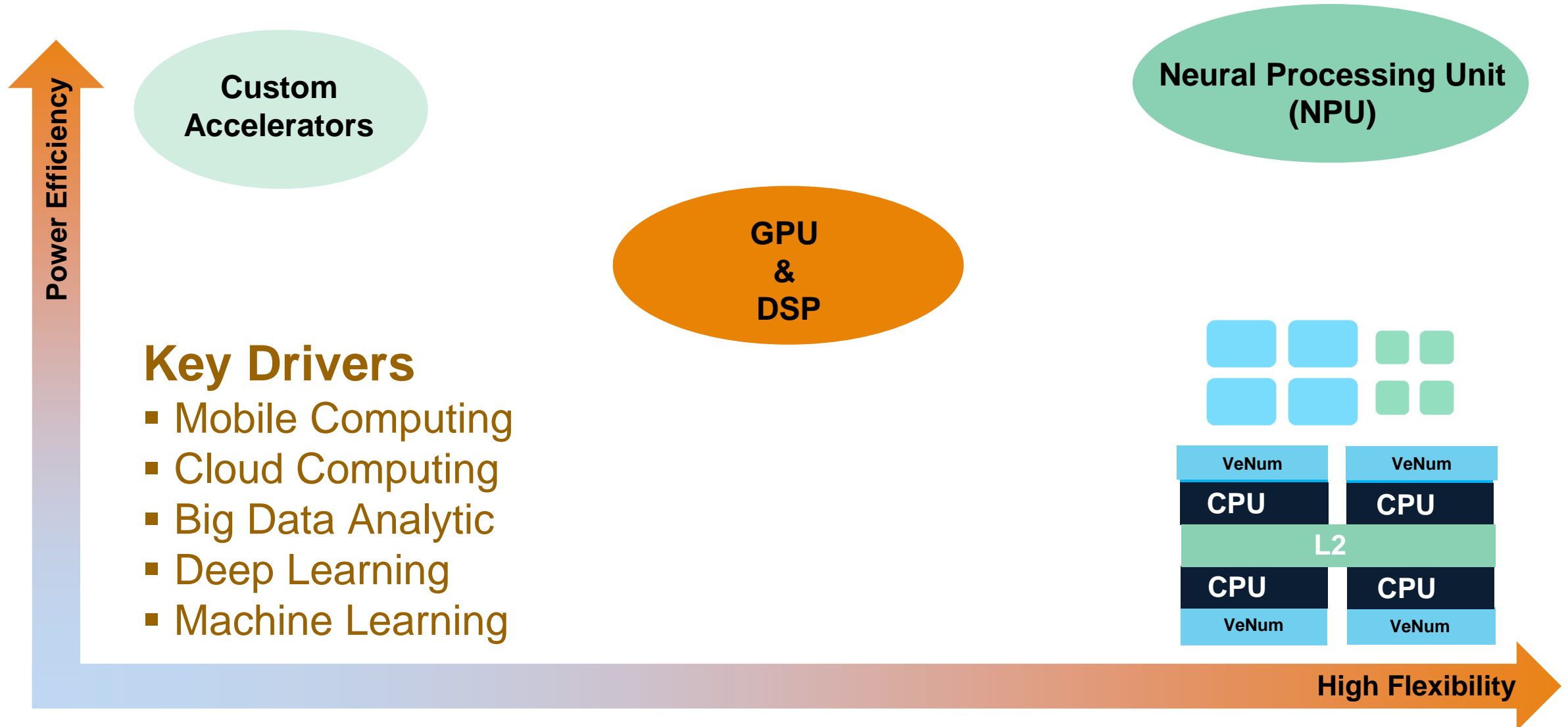
Set-top-boxes



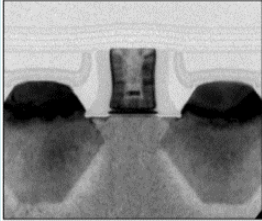
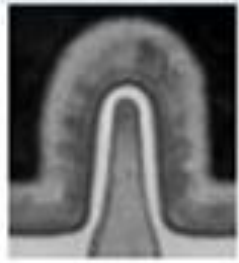
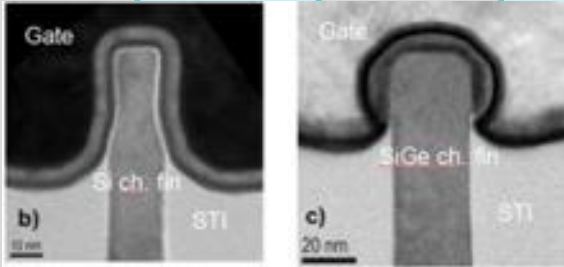
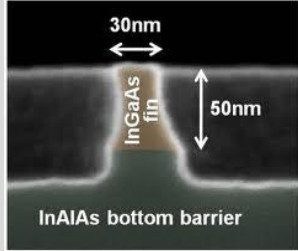
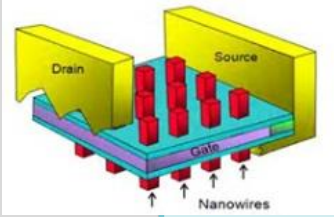
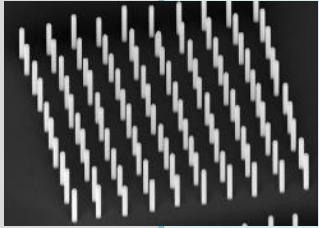
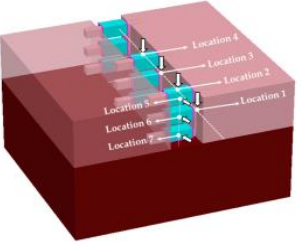
Cloud and Mobile Computing



Mobile Heterogeneous Compute Units to Lower Power



CMOS Scaling Outlook – The Roadmap Ahead

| | 2012 | 2013 | 2014 | 2015 | 2016 | 2017 | 2018 | 2019 | 2020 | 2021 |
|------------|---|------|---|------|--|------|--|------|---|------|
| Technology | 20nm | | 14nm | | 10nm | | 7nm | | 5nm | |
| Vdd | 1.0/0.9V 0.5V | | 0.9/0.8/0.7V | | 0.7/0.6V | | 0.6V | | | |
| Transistor | Planar/Tri-gate, Si channel | | FinFET, Si/SiGe/Ge | | FinFET, Si/SiGe/Ge | | FinFET/Nanowire SiGe/Ge/ III-V? | | Tunnel FET SiGe/Ge/III-V? | |
| |  Planar bulk RMG  Tri-gate, FinFET Si | |  FinFET Si/SiGe/Ge channel | |  FinFET III-V channel | |  Nanowire, vertical? | |  Tunnel FET, vertical? | |
| | | | | |  Nanowire, horizontal | | | | | |

CMOS Scaling Outlook – The Roadmap Ahead

Potential Issues to Address for 7nm and Beyond:

- FinFET/NWFET self-heating (phonon confinement)
- Feasibility of TFET and vertical channel devices
- System performance degradation (contact/BEOL bottleneck)

More Moore

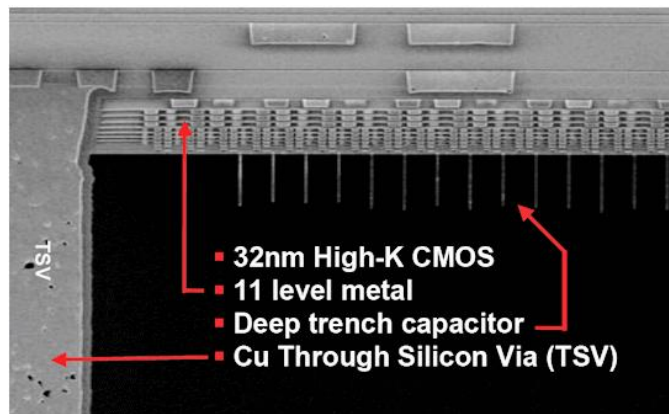
- Nano-wire
- TFET
- Ge/III-V

The 3rd Dimension

- 3DVLSI (3DV)
- MRAM & RRAM

Introduction: TSV-based 3D ICs

- **TSV-based 3D ICs are close to market**



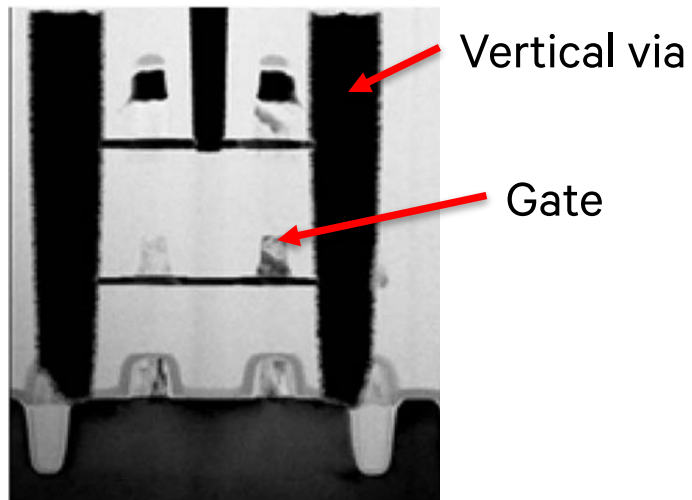
IBM (VLSI 2011)



TSMC (ISPD 2014)

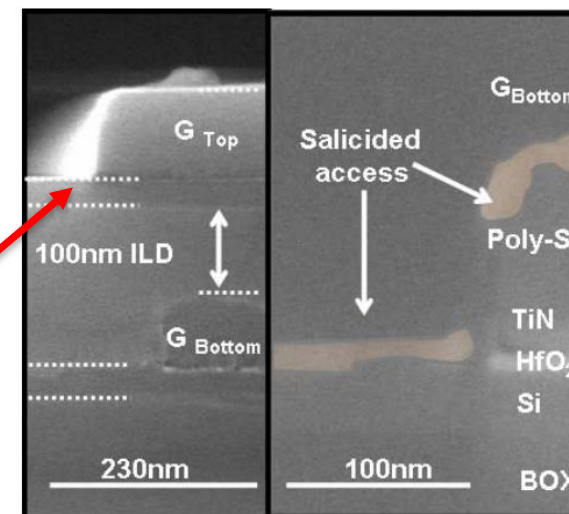
- **TSV-based 3D ICs shortens the interconnects, still quite large (5-10um, C=10-30fF)**

3D VLSI - An Emerging 3D Technology

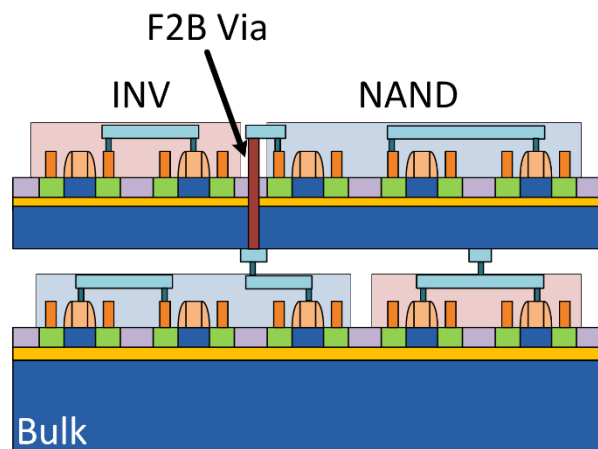


3D VLSI SRAM
Samsung (2010)

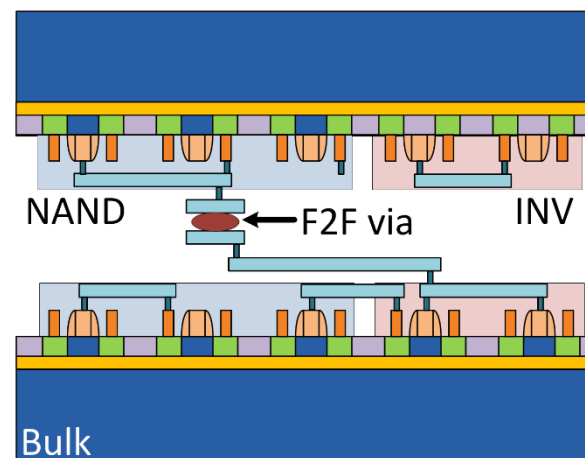
High quality thin silicon
(single crystal)



3D VLSI for general
logic LETI (2011)



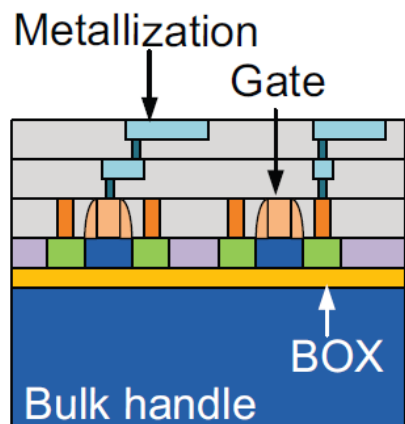
(a) Gate-Level F2B



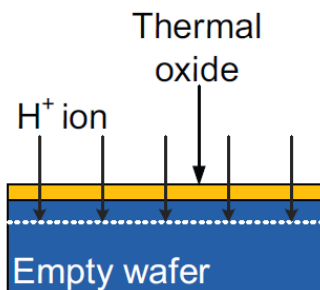
(b) Gate-Level F2F

Courtesy Panth et al., ISLPED'14

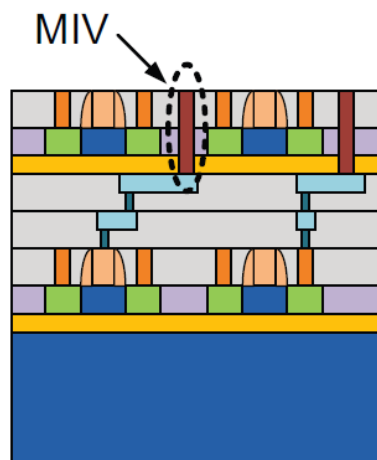
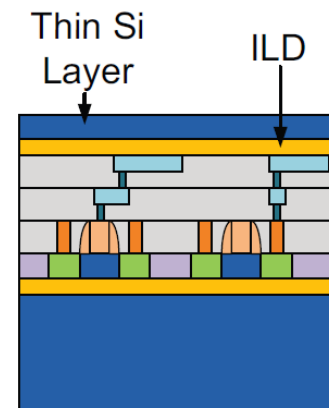
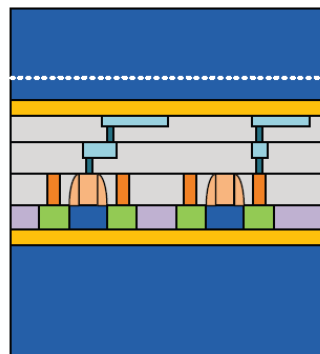
3D VLSI: Face-to-Back Fabrication Process



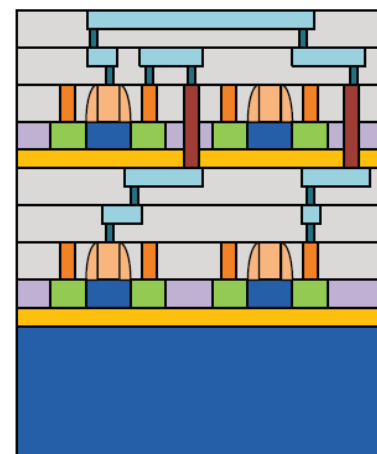
Bottom tier is created as usual



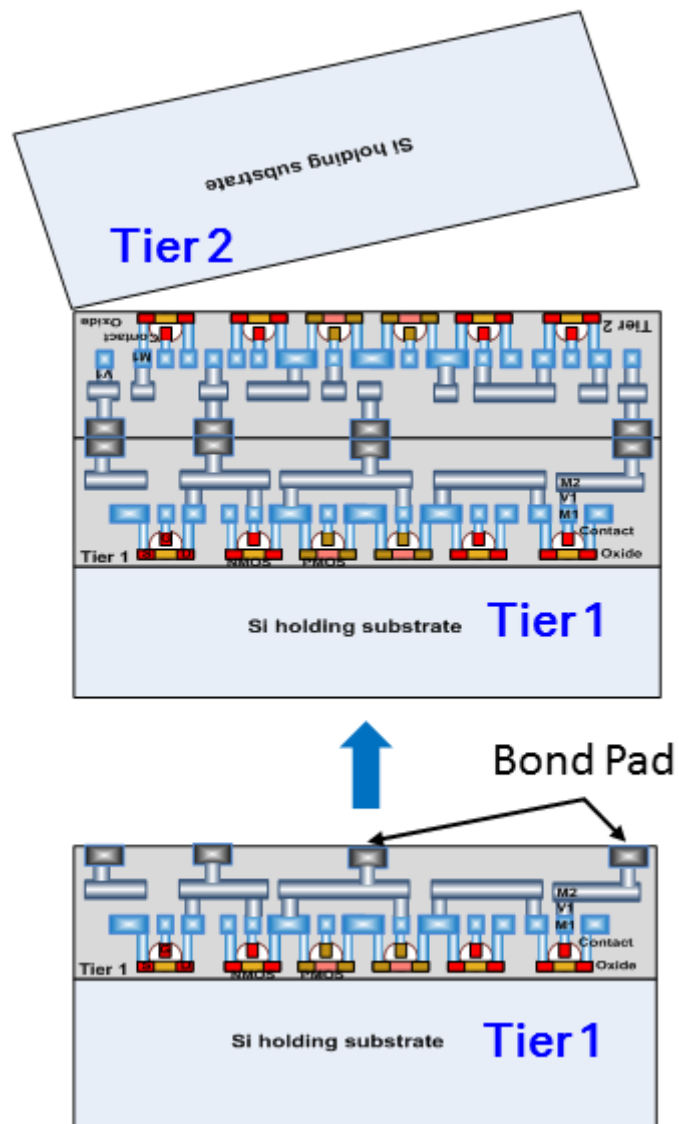
Thin Si layer is attached



Fabricate top-tier devices + interconnects



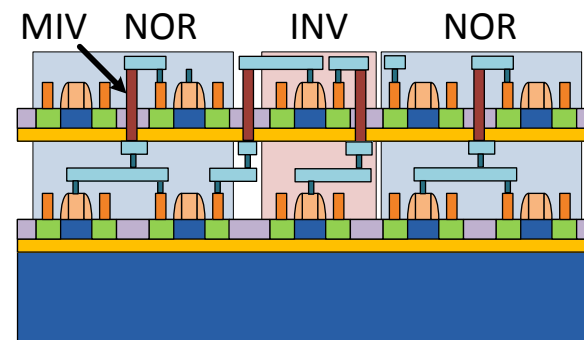
3D VLSI: Face-to-Face Fabrication Process



Design Styles Available in 3D VLSI (1/2)

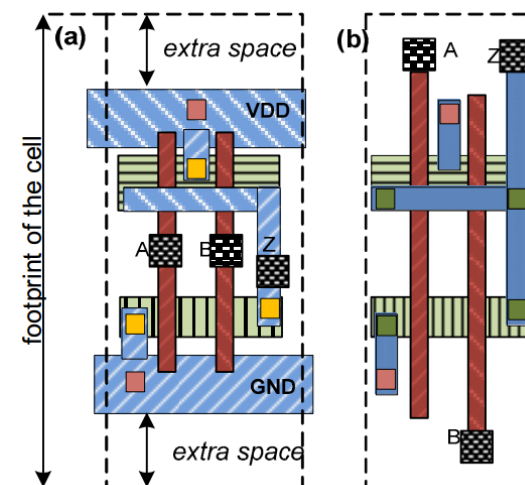
■ Transistor-level [1]

- Each standard cell is folded
- Pin density increases significantly
- Footprint reduction is ~40%, not 50%
- Standard cell re-design required



■ CELONCEL [2]

- Gate-level, but cell redesign required
- Simplified design flow
- Same disadvantages as transistor-level



[1] Y.-J. Lee, D. Limbrick and S. K. Lim, "Power Benefit Study for Ultra-High Density Transistor-Level Monolithic 3D ICs," DAC, 2013.

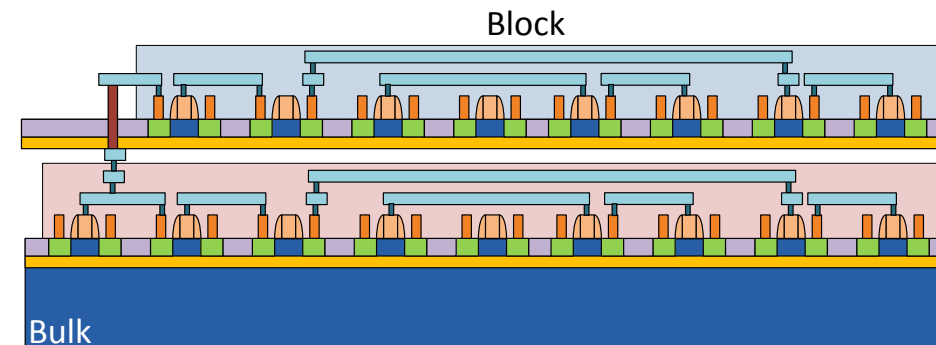
[2] S Bobba et al., "CELONCEL: Effective Design Technique for 3-D Monolithic Integration targeting High Performance Integrated Circuits," ASPDAC, 2011.

Courtesy Panth et al., ISLPED'14

Design Styles Available in 3D VLSI (2/2)

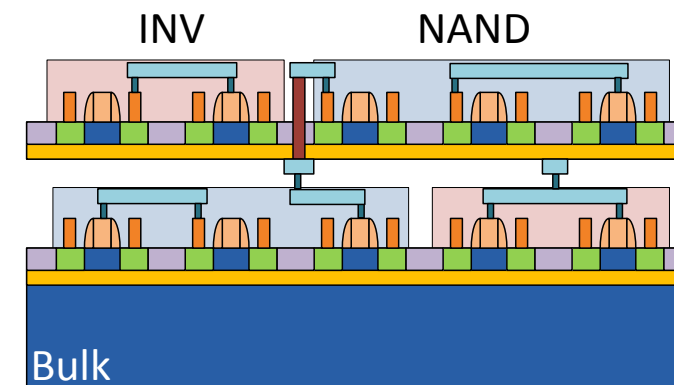
■ Block-level [1]

- Functional blocks are 2D & they are floorplanned on to a 3D space
- Reuse of IP
- Does not fully take advantage of the high density offered by M3D



■ Gate-level

- Use existing standard cells & place them in 3D
- Reuse of cells



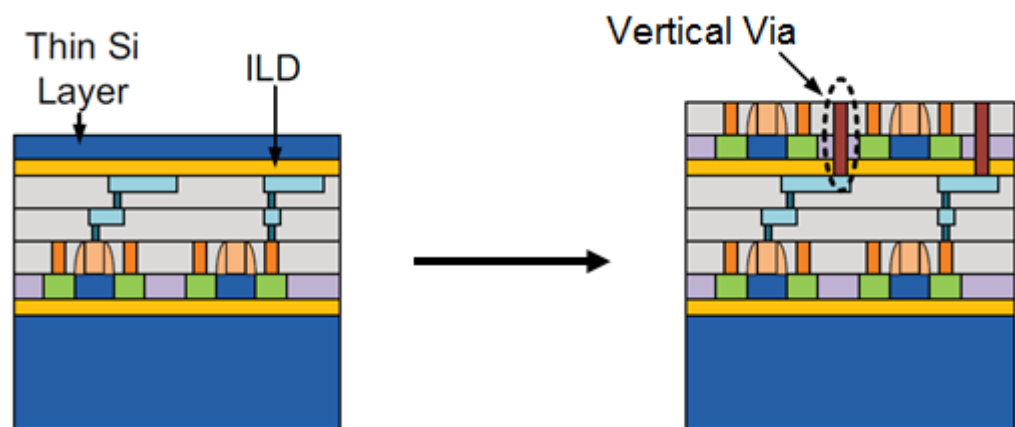
[1] S. Panth et al. "Power-Performance Study of Block-Level Monolithic 3D-ICs Considering Inter-Tier Performance Variations", DAC, 2014.

Courtesy Panth et al., ISLPED'14

Block-Level 3D VLSI Physical Implementation



Sequential 3D: Source of Inter-Tier Performance Variation

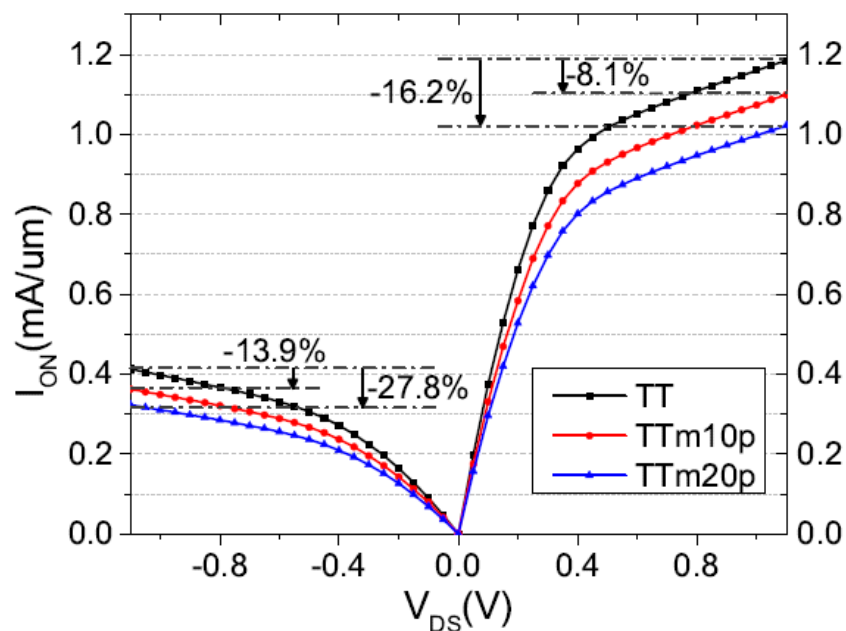


- **FEOL processing of top tier**
 - **RTA at 1200C will damage both devices and interconnects**

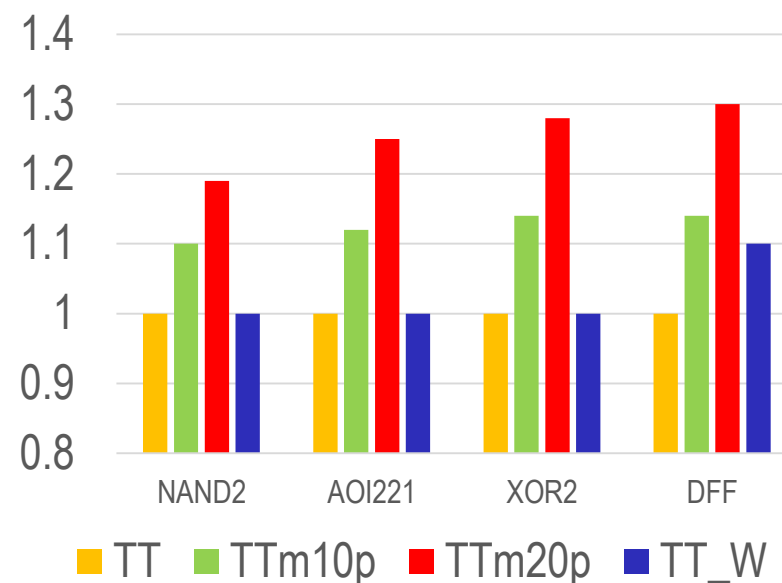
- **Process improvement: < 625C without performance loss → still too high for Cu interconnect**
- **Preventing damage to interconnects – Two options:**
 - **Use Tungsten (W) on the bottom tier → Worse interconnects on bottom tier**
 - **Identical devices on both tiers**
 - **~ 450C processing on the top tier → Worse transistors on the top tier**
 - **Identical interconnects on both tiers**

Degraded Transistors

- PMOS worsens by 27.8% and NMOS worsen by 16.2% (TTm20p corner)



Change in delays of select standard cells

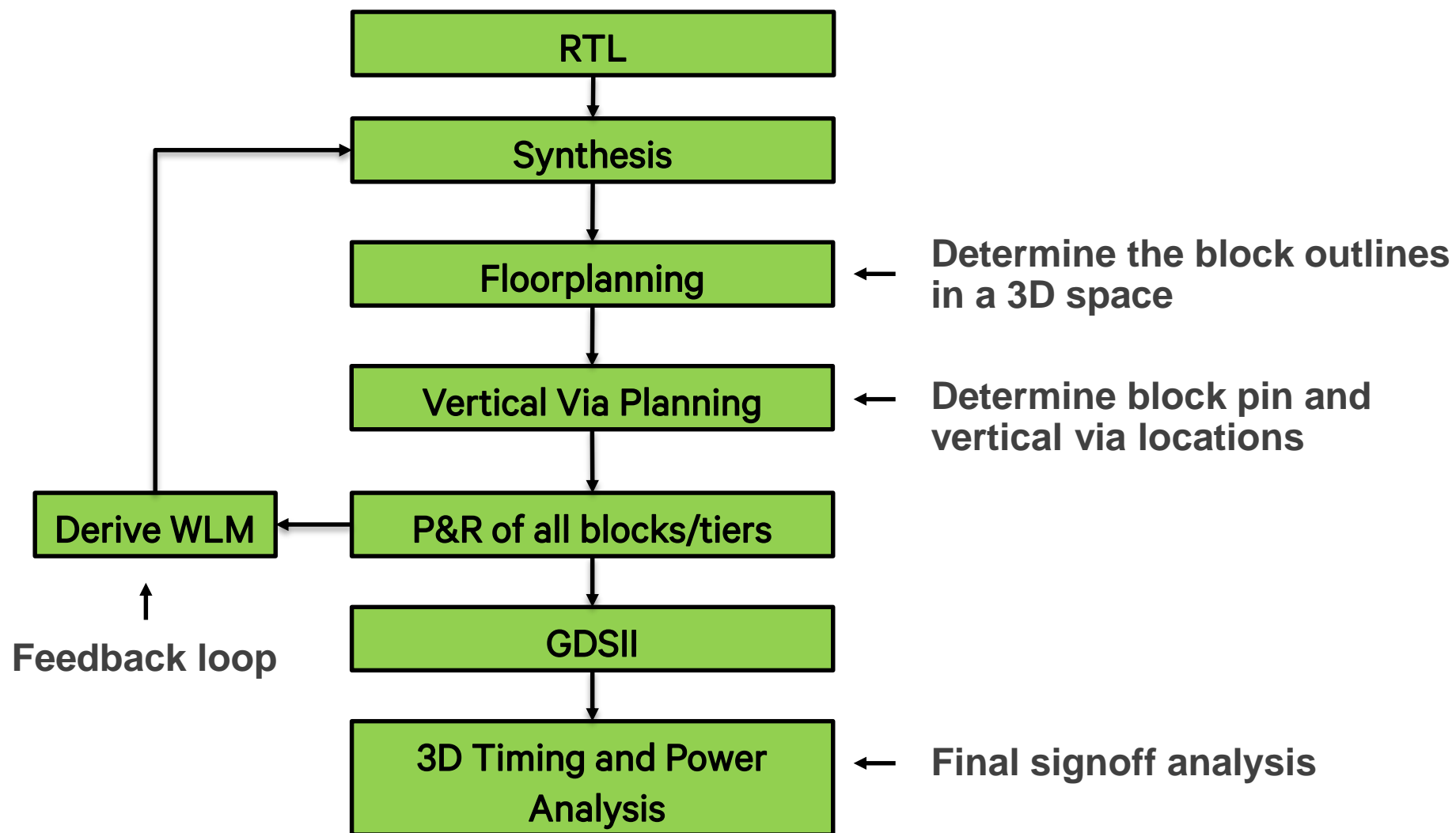


↑
Identical devices, but
W interconnect

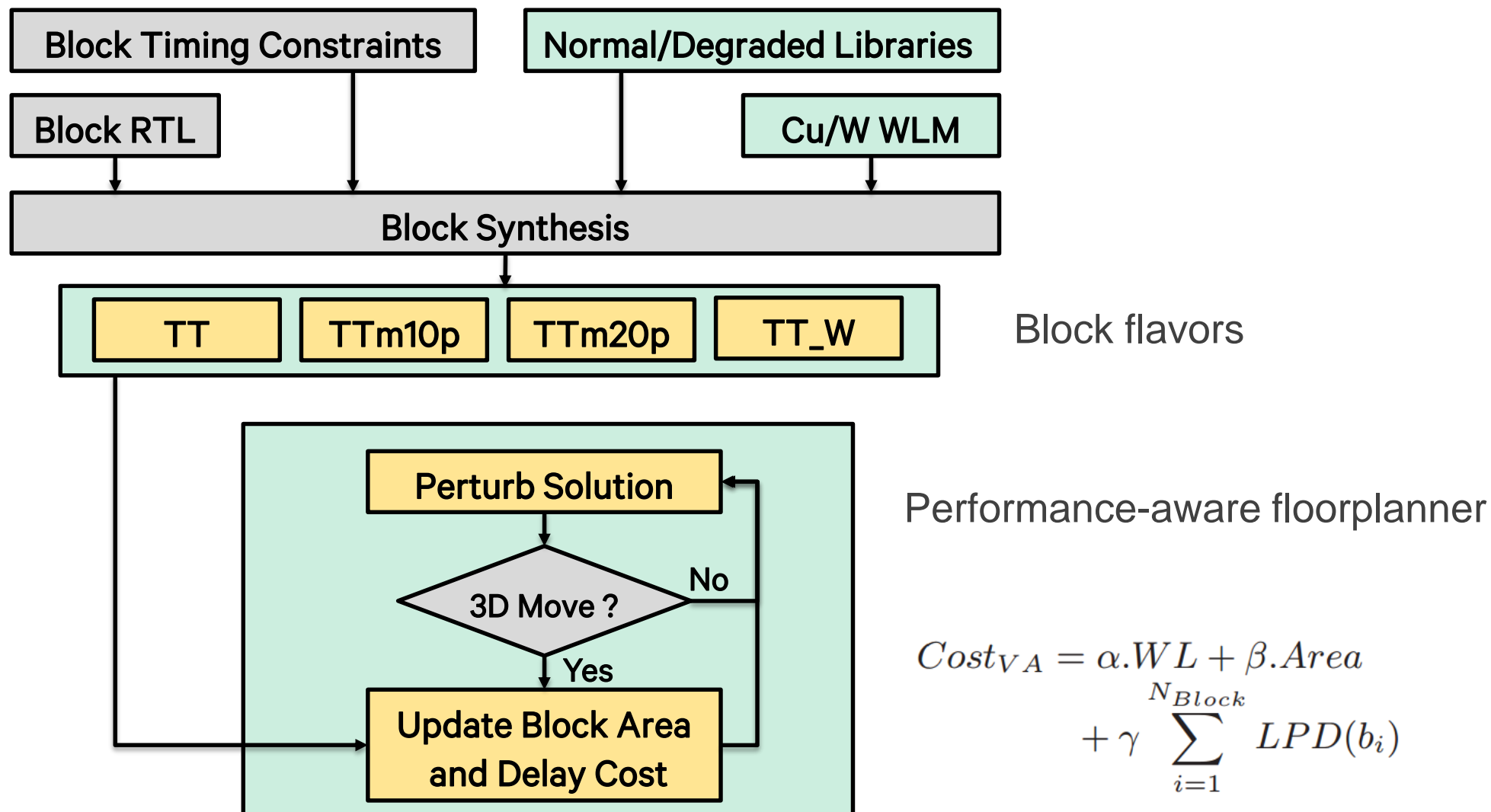
[1] Low Thermal Budget Processing for Sequential 3D IC Fabrication, Rajendran et al., TED, 2007

Courtesy Panth et al., DAC'14

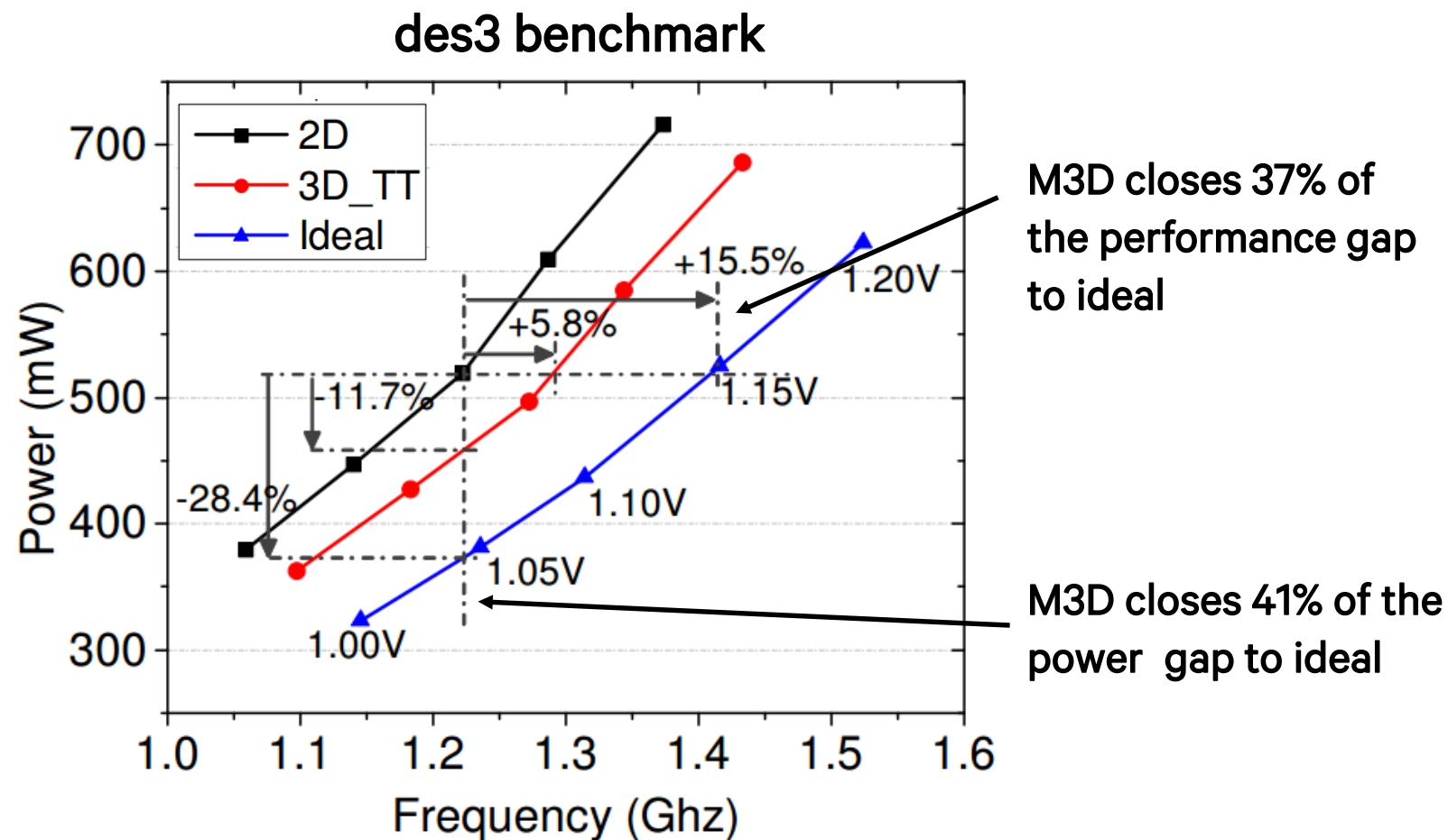
Design Flow



Variation-Aware 3D Block-Level Floorplanning

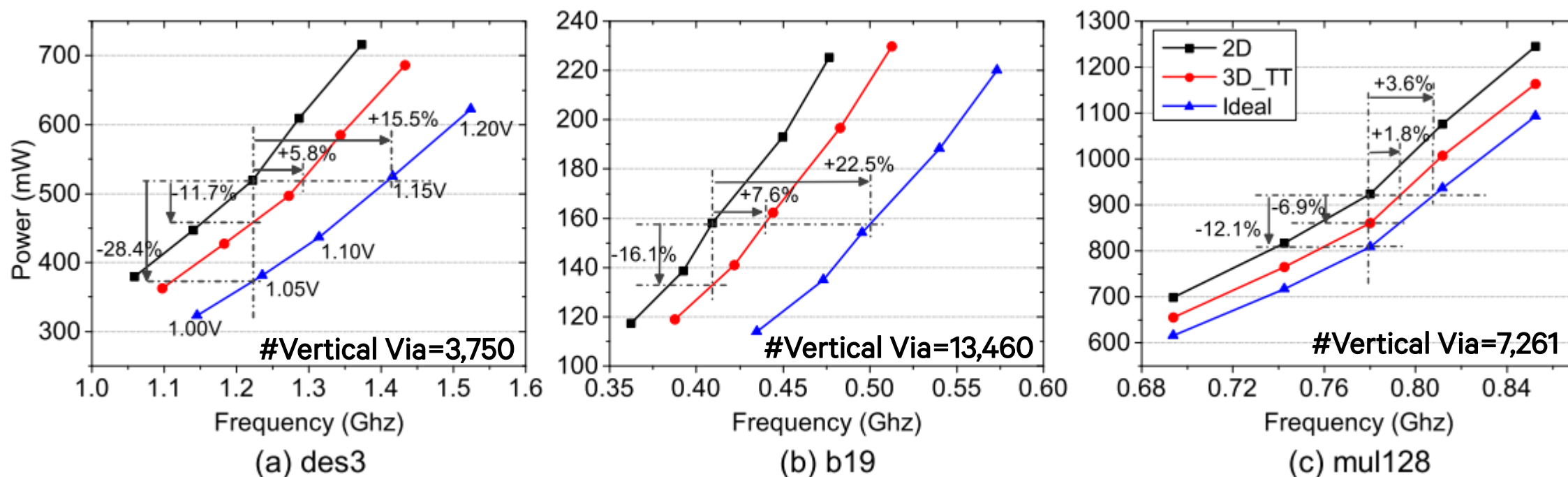


Power-Performance Study: Identical Tier Performance



- **Ideal: Zero RC for inter-block nets: Best possible block-level implementation**

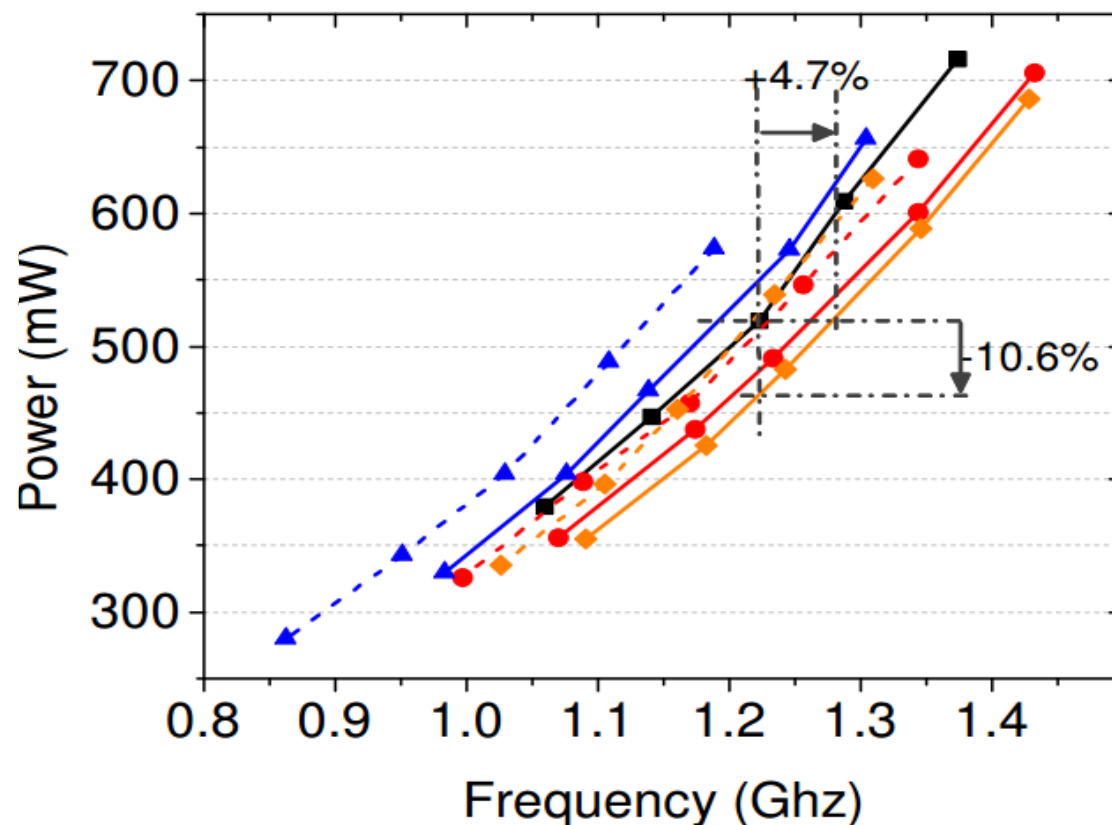
Power-Performance Study: Identical Tier Performance



- **Similar results for all benchmarks**
- **3D closes the power gap to ideal by at least 40%**
- **3D closes the performance gap to ideal by up to 50% and 40% on average**

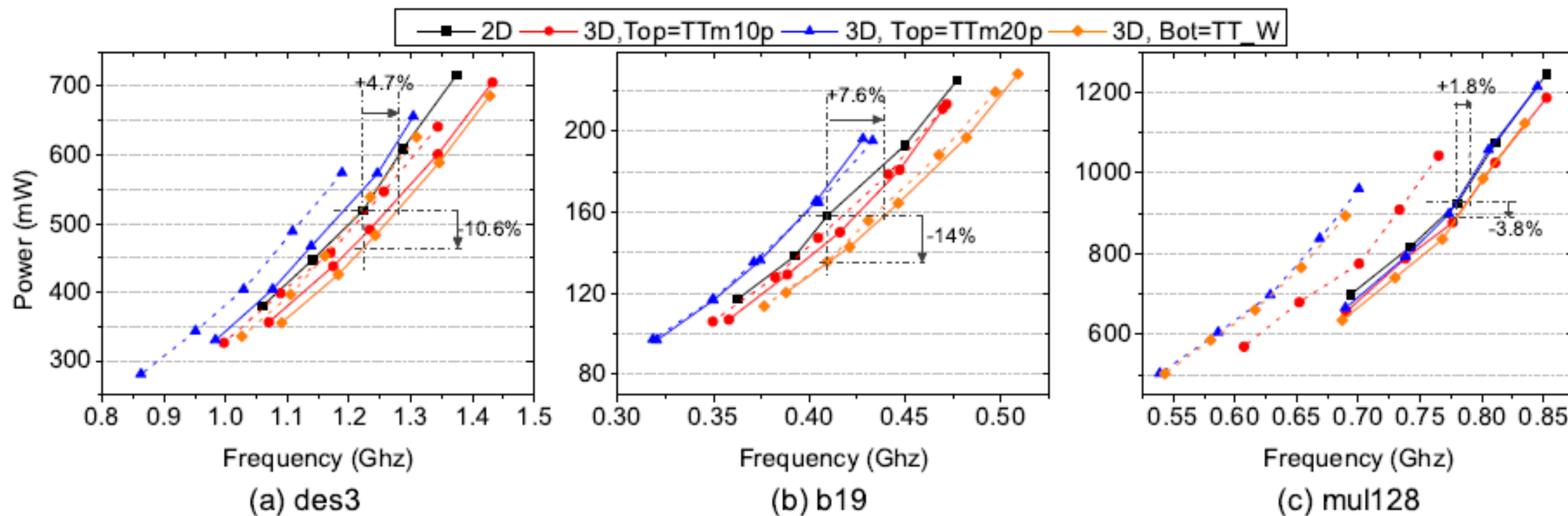
Variation-Aware Power-Performance Results

—■— 2D —▲— 3D, Top=TTm20p —●— 3D, Top=TTm10p —◆— 3D, Bot=TT_W



- Dashed lines = no variation-aware floorplanning
- Solid lines = variation-aware floorplanning

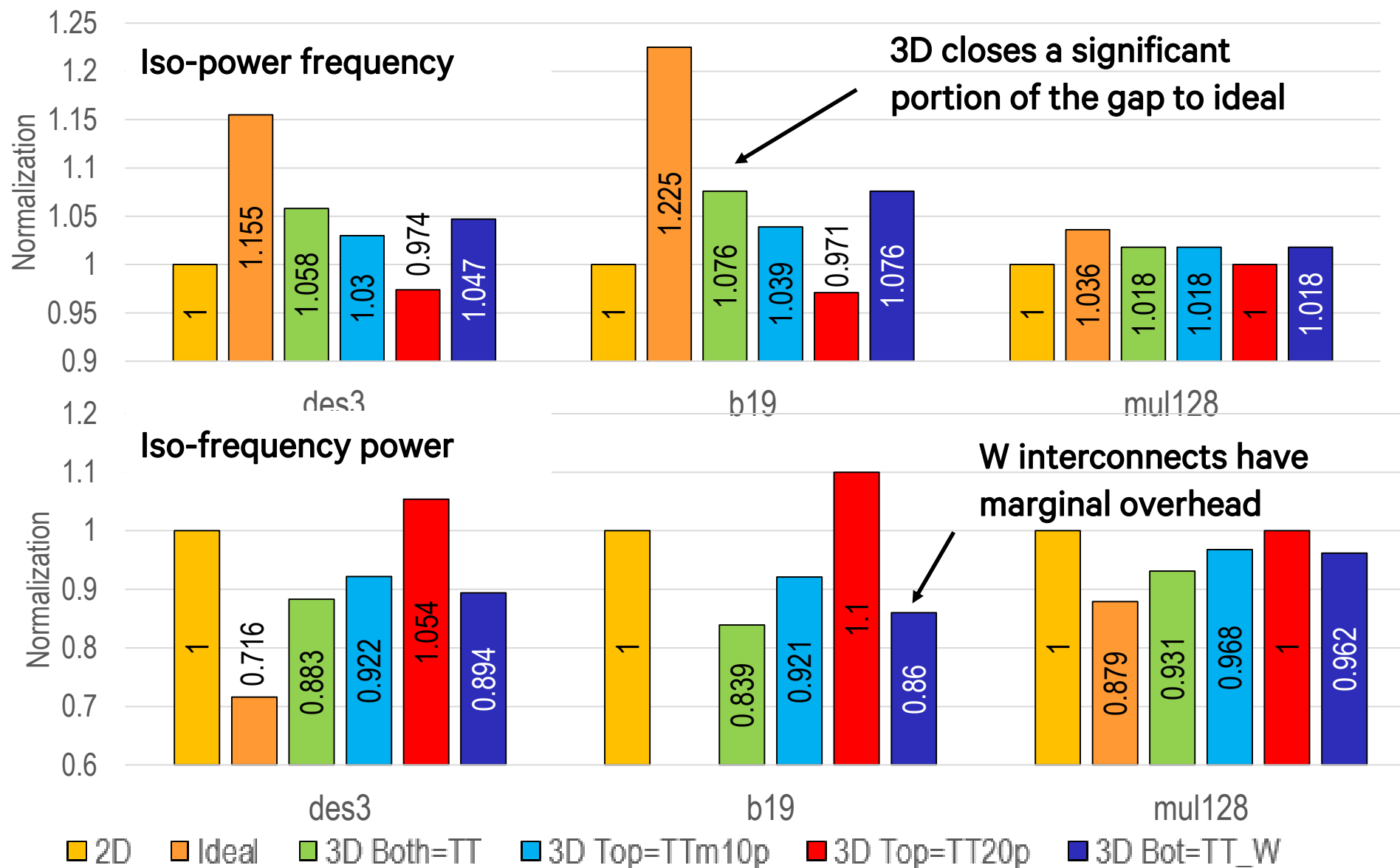
Variation-Aware Power-Performance Results



- Variation-aware floorplanning always gives better results
- W on the bottom tier seems to be the best option

Courtesy Panth et al., DAC'14

Summary of Results



Courtesy Panth et al., DAC'14

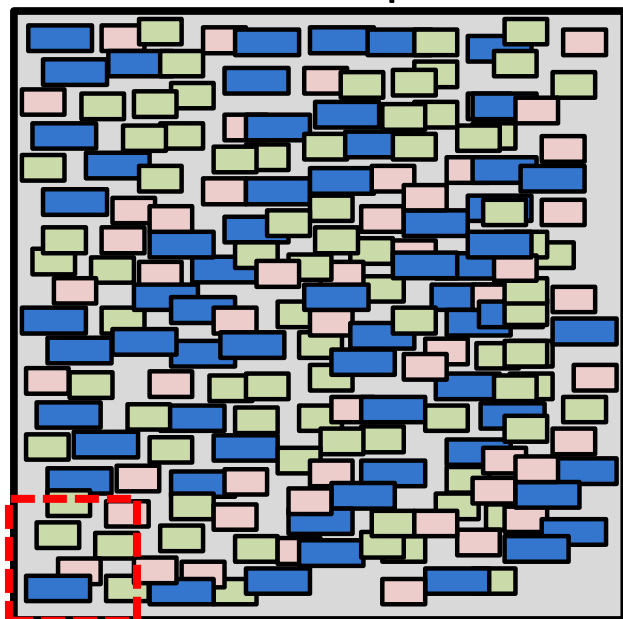
Gate-Level 3D VLSI Physical Implementation



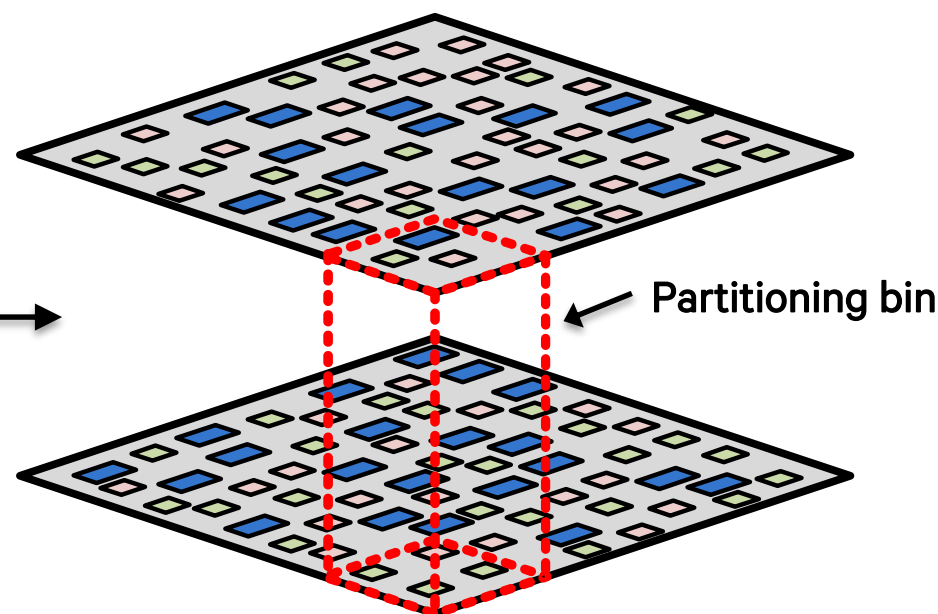
Initial Work in Gate-level 3D VLSI

- Placement-driven partitioning using academic placers [1]

First, make the 3D footprint 50% of 2D



In a 2D placer, double the placement capacity of each global bin (for two-tier)



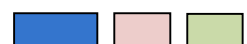
Partition the design, maintaining local area balance within each partitioning bin
 “Placement-driven Partitioning”

[1] S. Panth et. al., "Placement-Driven Partitioning for Congestion Mitigation in Monolithic 3D IC Designs", ISPD, 2014.

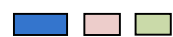
Courtesy Panth et al., ISLPED'14

“Shrunk 2D” Placement using a Commercial Tool

- In a commercial tool, we cannot “double” the supply.
- Instead, we first halve the std. cell areas (multiply W/H by 0.707)



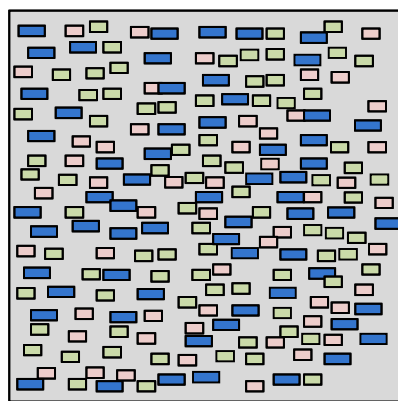
Original 2D
Std. Cells



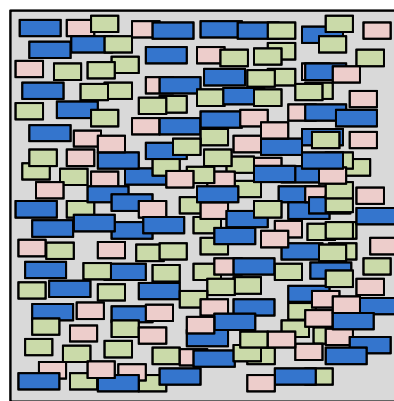
Shrunk 2D
Std. Cells

Note: We **do not** touch the .lib file → Timing information is maintained

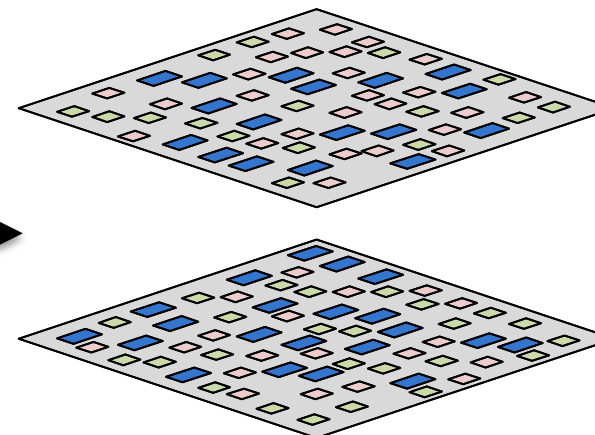
$$W = 0.707 * W_{2D}$$



Shrunk 2D Placement



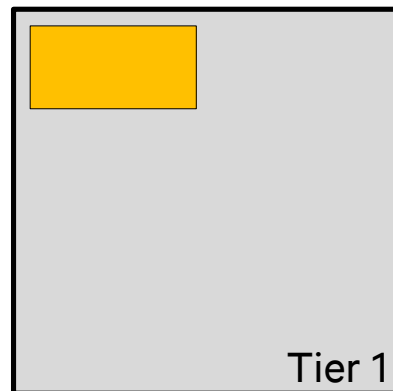
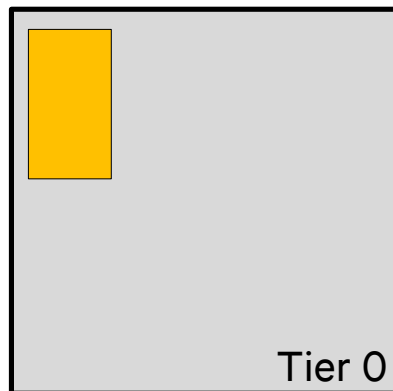
Cell Expansion



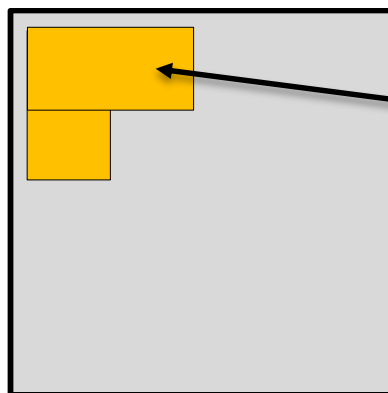
Placement-driven Partitioning

Handling Memory Macros: Issues

- Memory is usually pre-placed before placement starts



- We cannot simply superimpose them before feeding it to the commercial tool for shrunk 2D P&R

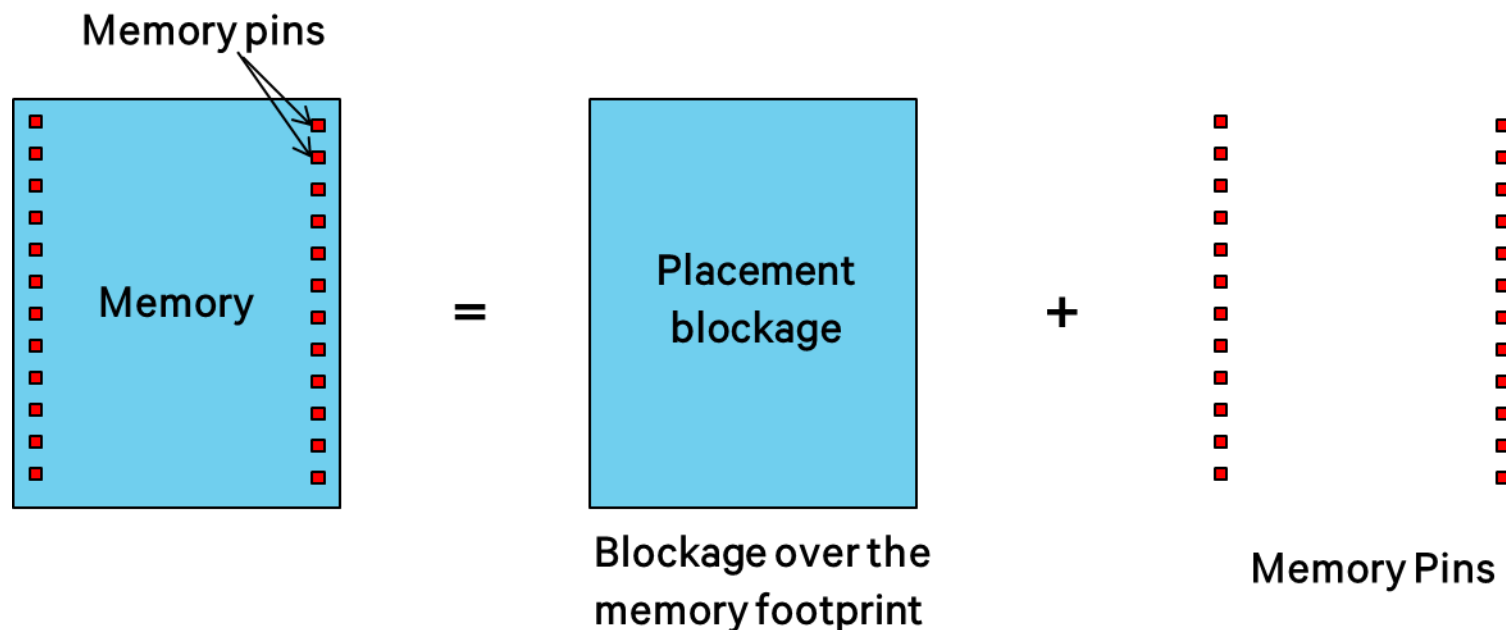


Shrunk 2D Footprint

This will cause a placement blockage in these regions, which is wrong

Handling Memory Macros: Decomposition

- Memory macros can be thought of as a combination of a placement blockage and memory pins



- If we can isolate each component, then they can be handled separately during shrunk 2D P&R

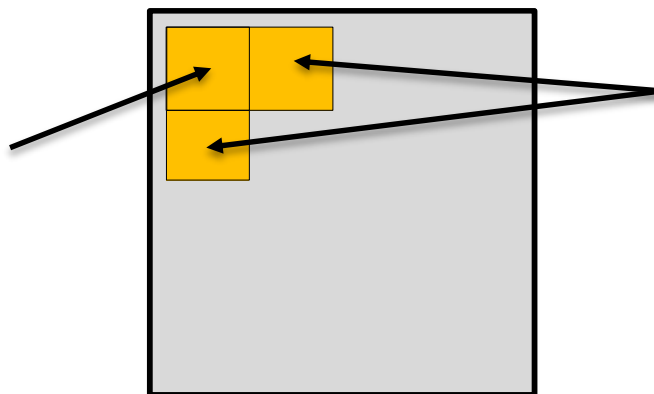
Handling Memory Placement Blockages (1/2)

- Consider the two memory regions overlapping as shown earlier

This region has memory in both tiers

After partitioning, neither tier will contain cells

Therefore, it will be a full placement blockage in the shrunk 2D footprint

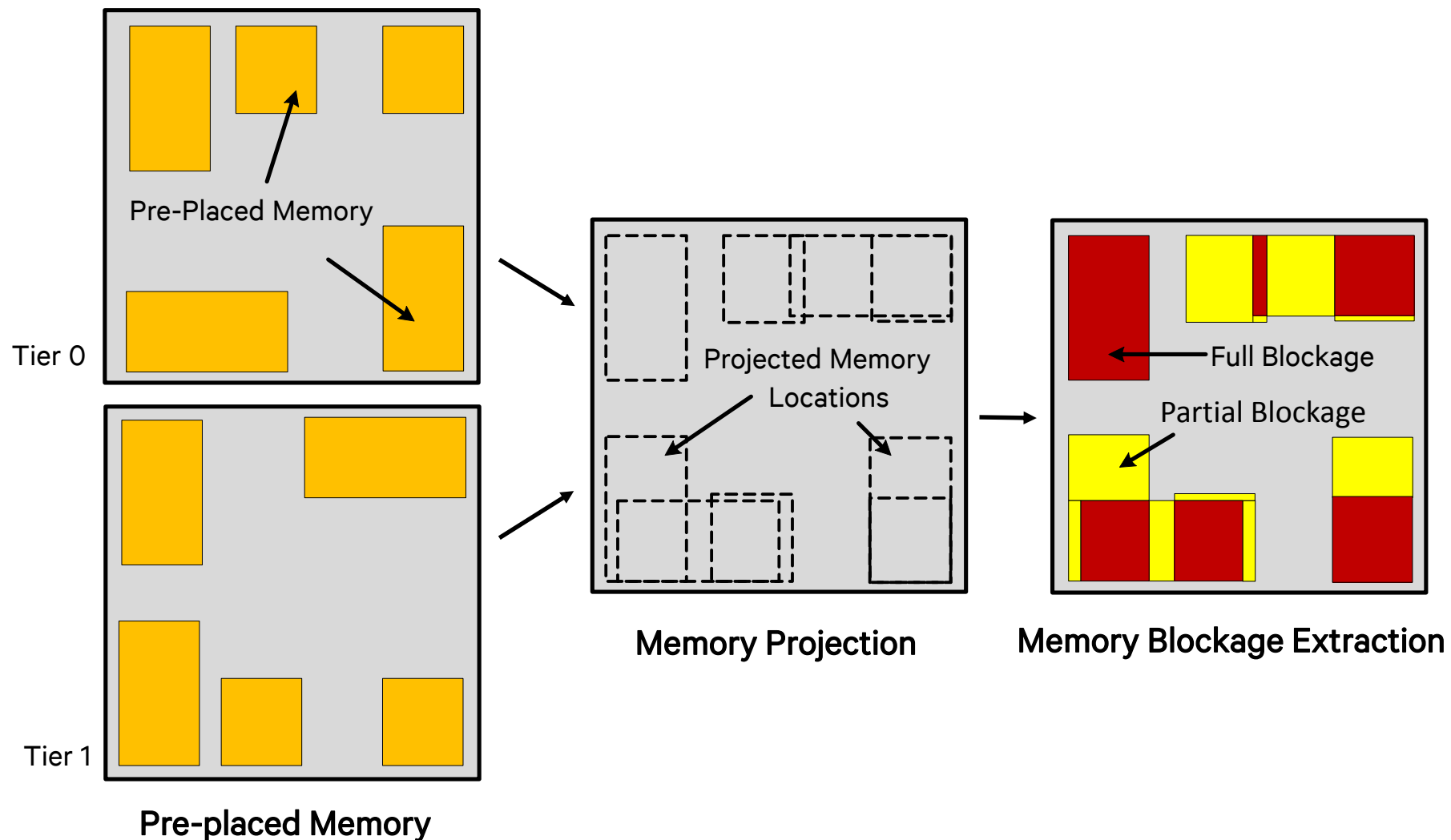


These regions have memory in one tier only → The other tier can contain cells

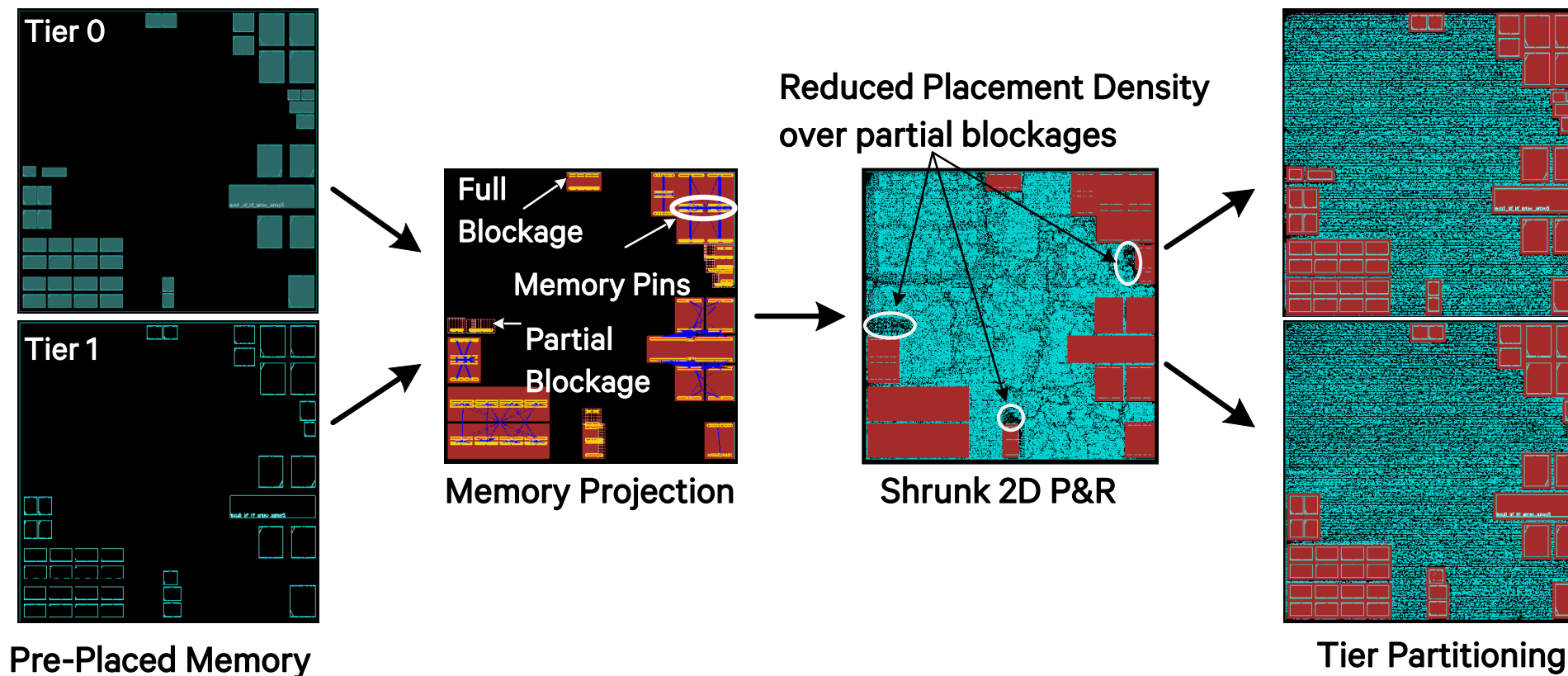
If the target density = 70% in the final 3D design, we set the max density of these regions = 35% (=70% once cells are expanded back to original area)

This can be achieved by creating a partial placement blockage in these areas

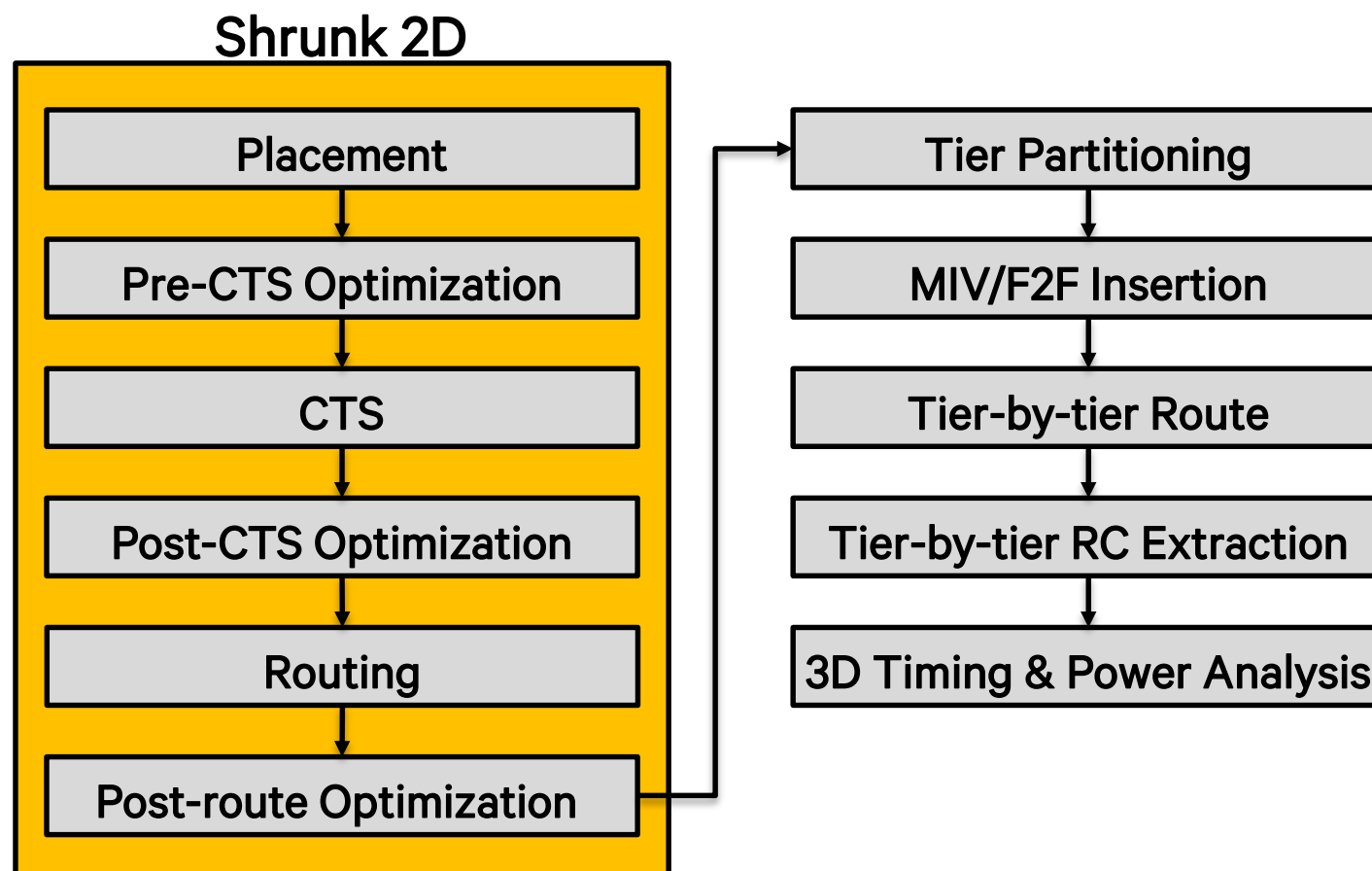
Handling Memory Placement Blockages (2/2)



Design Flow Screenshots

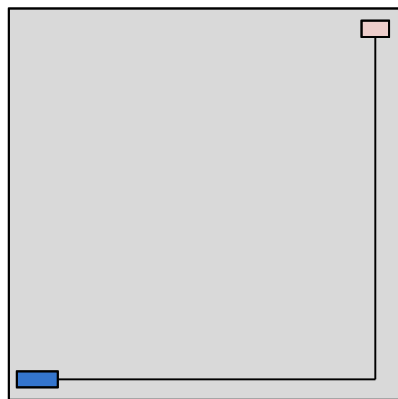


Design Flow

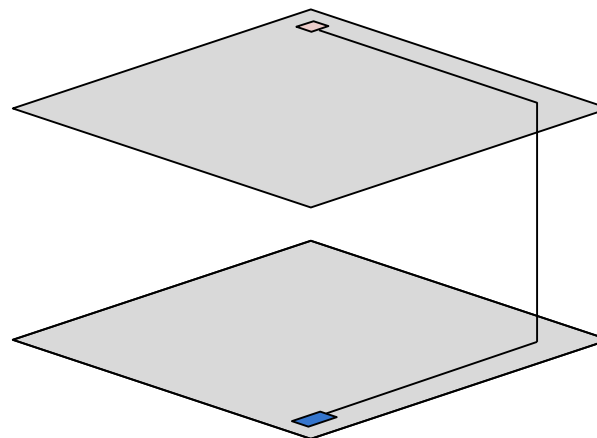


Matching Wire Parasitics between Shrunk 2D and 3D

- Consider two cells connected to each other in Shrunk 2D & then in 3D



$$L_{S2D} = L_x + L_y$$

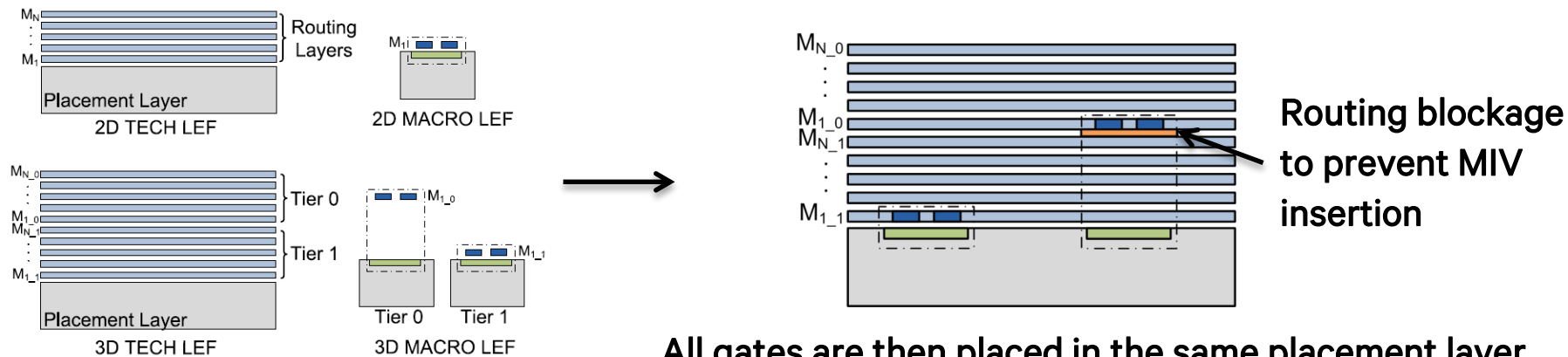


$$L_{3D} = L_x + L_y + L_{MIV}$$

- But $L_{MIV} < 1\mu\text{m}$. Therefore $L_{S2D} \approx L_{3D}$
- However, the wire widths are different; $W_{S2D} = 0.707 W_{3D}$
- Since we want $R_{S2D} \approx R_{3D}$ and $C_{S2D} \approx C_{3D}$, we **do not scale** the per-unit-length RC values in the cap table file for shrunk 2D design.

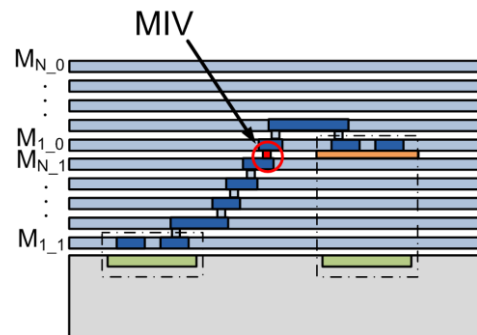
Vertical Via Insertion (Face-to-Back)

- Trick the commercial router into inserting MIVs for us [1]

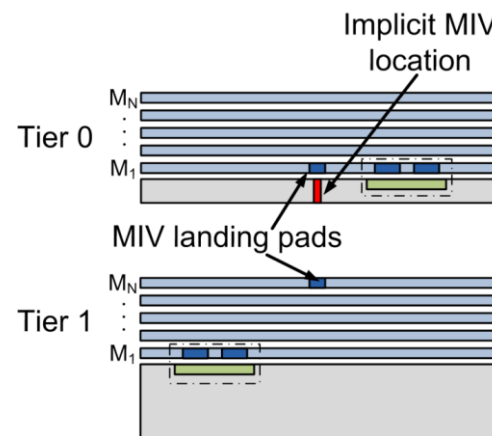


All gates are then placed in the same placement layer

LEF files are modified for 3D



Route with Encounter

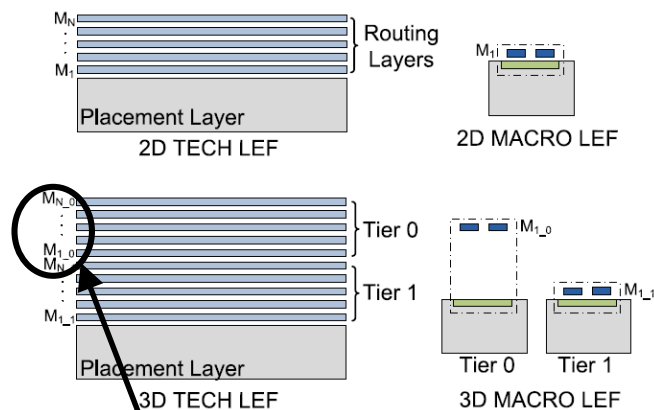


Create separate verilog/DEF for each tier

[1] S. Panth et. Al., "Placement-Driven Partitioning for Congestion Mitigation in Monolithic 3D IC Designs", ISPD 2014.

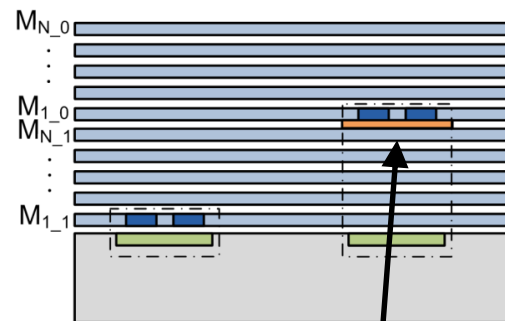
Courtesy Panth et al., ISLPED'14

Vertical Via Insertion (Face-to-Face)



LEF files are modified for 3D

Reverse the order of metals in Tier 0



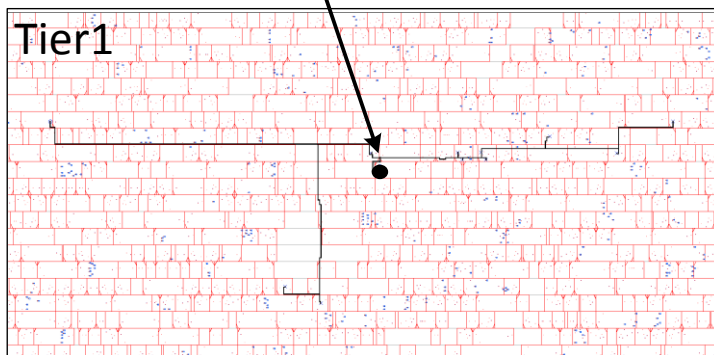
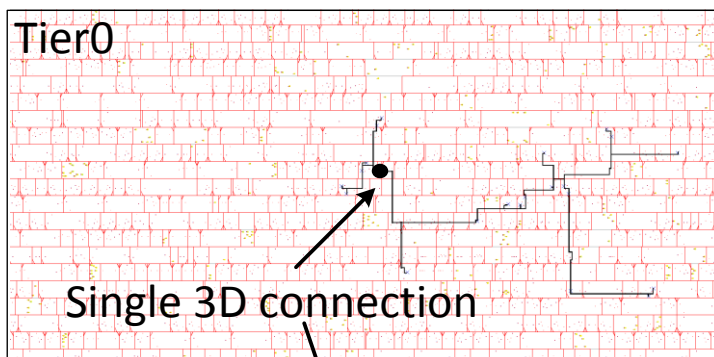
All gates are then placed in the same placement layer

Do not add any routing blockage to prevent F2F insertion over cells

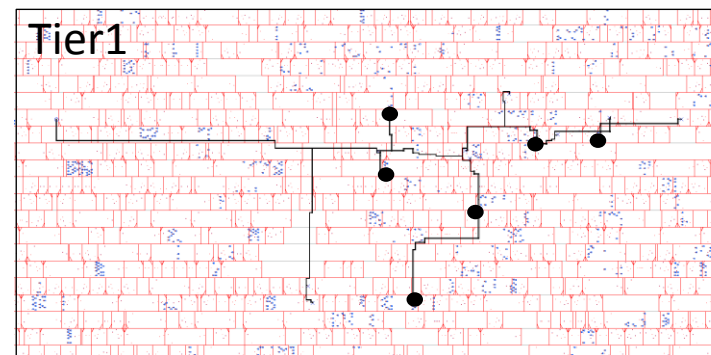
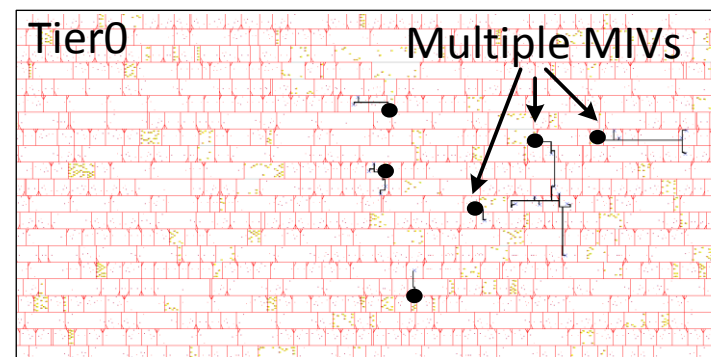
Single vs. Multiple MIV Insertion: Screenshots

- Conventional 3D flows have a tier-by-tier optimization step
- It is very difficult to derive timing budgets for multiple MIVs per net
- Shrunk 2D flow enables multiple MIV insertion → Lower WL and power

Single MIV Insertion



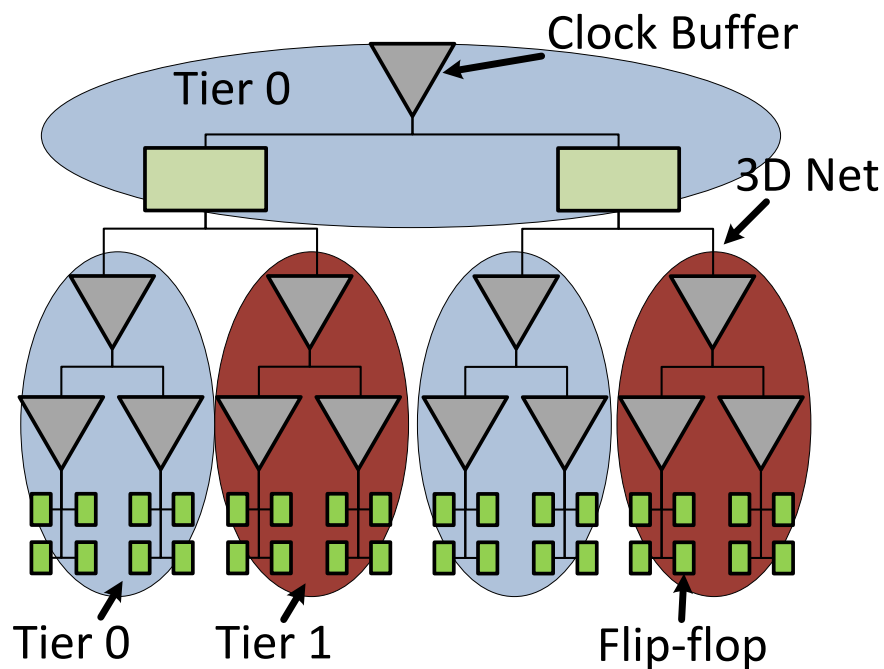
Multiple MIV Insertion



Single vs. Multiple Vertical Via Insertion: Results

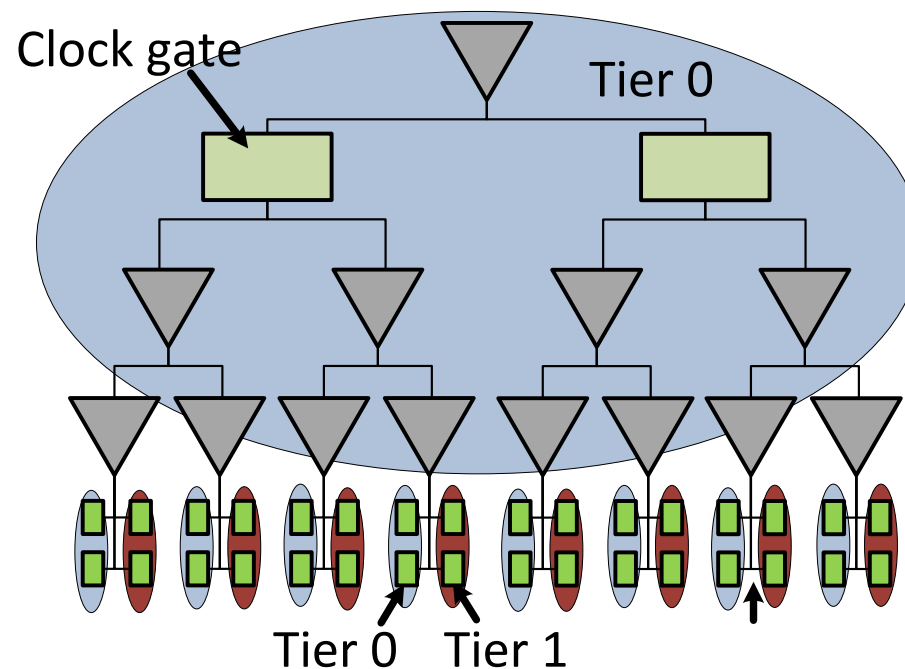
| | F2B 3D | | F2F 3D | |
|------------------|--------|-----------------|--------|-----------------|
| | Single | Multiple | Single | Multiple |
| Total WL (m) | 15.61 | 14.29 (-8.43%) | 15.44 | 13.89 (-10.05%) |
| #MIV/F2F | 106k | 235k (+120.44%) | 106k | 202k (+89.72%) |
| | | | | |
| Total Power (mW) | 534.10 | 522.10 (-2.25%) | 538.30 | 524.00 (-2.66%) |
| | | | | |
| Cell Power (mW) | 126.90 | 126.10 (-0.63%) | 127.30 | 126.40 (-0.71%) |
| Net Power (mW) | 293.90 | 282.70 (-3.81%) | 297.80 | 284.30 (-4.53%) |
| Leak. Power (mW) | 113.30 | 113.30 (+0.0%) | 113.30 | 113.30 (0.00) |

3D Clock-Tree Synthesis



Traditional 3D CTS: Source-level

One clock-tree per clock-gating group in each tier, tied together at the root level



Proposed 3D CTS: Leaf-level

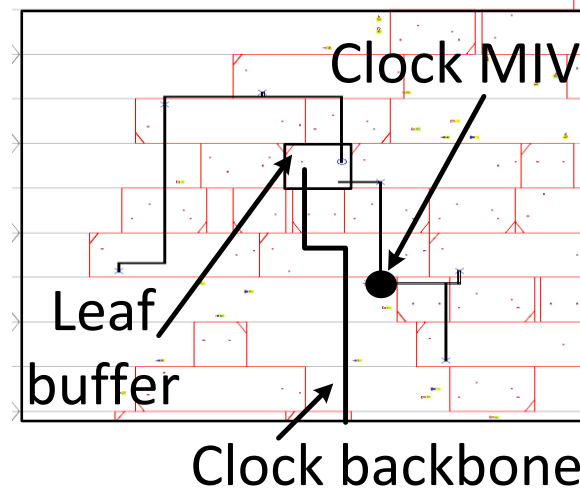
Keep **the entire backbone on one tier**. Only insert clock MIVs to connect the FF on different tiers at the leaf level

Leaf-Level CTS: Screenshots

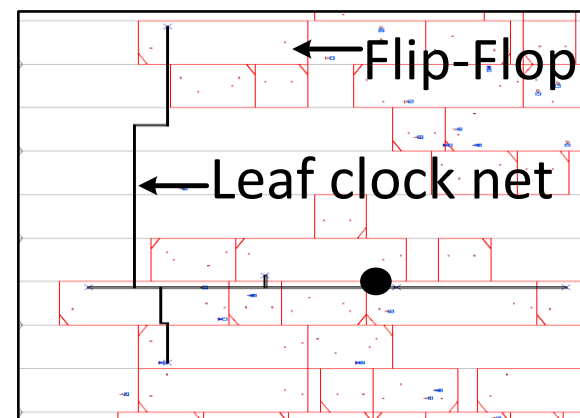
Clock back-bone on Tier 0



Zoom in of red rectangle



Leaf clock
net on Tier 0



Leaf clock
net on Tier 1

CTS Results

| | F2B 3D | | F2F 3D | |
|---------------------|--------------|------------------|--------------|------------------|
| | Source-level | Leaf-level | Source-level | Leaf-level |
| #Vertical Via | 871 | 11,376 (+1.2k%) | 871 | 11,376 (+1.2k%) |
| Clock Skew (ps) | 197.42 | 103.00 (-47.83%) | 172.90 | 117.07 (-32.29%) |
| | | | | |
| Clock Power (mW) | 68.40 | 48 (-29.82%) | 69.00 | 48.50 (-29.71%) |
| | | | | |
| Clk WL – Tier 0 (m) | 0.55 | 0.62 (+11.89%) | 0.53 | 0.62 (+16.61%) |
| Clk WL – Tier 1 (m) | 0.48 | 0.19 (-60.50) | 0.48 | 0.17 (-64.85%) |
| Total Clk WL (m) | 1.03 | 0.80 (-21.67%) | 1.01 | 0.79 (-21.91%) |
| | | | | |
| # Clk Buf – Tier 0 | 14,610 | 21,687 (+48.44%) | 14,958 | 21,687 (+44.99%) |
| # Clk Buf – Tier 1 | 12,444 | 0 (-100%) | 12,691 | 0 (-100%) |
| Total # Clk Buf | 27,054 | 21,687 (-19.84%) | 27,649 | 21,687 (-21.56%) |

Single Vt Power Comparisons (mW)

| | Encounter 2D | Shrunk 2D | F2B 3D | F2F 3D |
|---------------|--------------|------------------|------------------|------------------|
| Total | 618.40 | 514.40 (-16.82%) | 522.10 (-15.57%) | 524.00 (-15.27%) |
| Cell | 135.60 | 126.80 (-6.49%) | 126.10 (-7.01%) | 126.40 (-6.78%) |
| Net | 356.30 | 274.30 (-23.01%) | 282.70 (-20.66%) | 284.30 (-20.21%) |
| Leakage | 126.50 | 113.30 (-10.43%) | 113.30 (-10.43%) | 113.30 (-10.43%) |
| Memory | 49.00 | 45.10 (-7.96%) | 45.10 (-7.96%) | 45.00 (-8.16%) |
| Combinational | 385.10 | 300.00 (-22.10%) | 305.30 (-20.72%) | 306.80 (-20.33%) |
| Clock Tree | 62.50 | 46.90 (-24.96%) | 48.00 (-23.20%) | 48.50 (-22.40%) |

Dual Vt Power Comparisons (mW)

| | Encounter 2D | Shrunk 2D | F2B 3D | F2F 3D |
|---------------|---------------|------------------------|-------------------------|-------------------------|
| Total | 572.10 | 471.4 (-17.60%) | 480.10 (-16.08%) | 482.20 (-15.71%) |
| | | | | |
| Cell | 131.80 | 122.5 (-7.06%) | 123.00 (-6.68%) | 123.30 (-6.45%) |
| Net | 356.60 | 274.2 (-23.11%) | 282.70 (-20.72%) | 284.30 (-20.27%) |
| Leakage | 83.60 | 74.7 (-10.65%) | 74.70 (-11.00%) | 74.60 (-10.77%) |
| | | | | |
| Memory | 48.80 | 45.1 (-7.58%) | 45.10 (-7.58%) | 45.00 (-7.79%) |
| Combinational | 361.60 | 278.6 (-22.95%) | 283.00 (-21.74%) | 284.30 (-21.38%) |
| Clock Tree | 62.50 | 47.3 (-24.32%) | 48.00 (-23.20%) | 48.50 (-22.40%) |

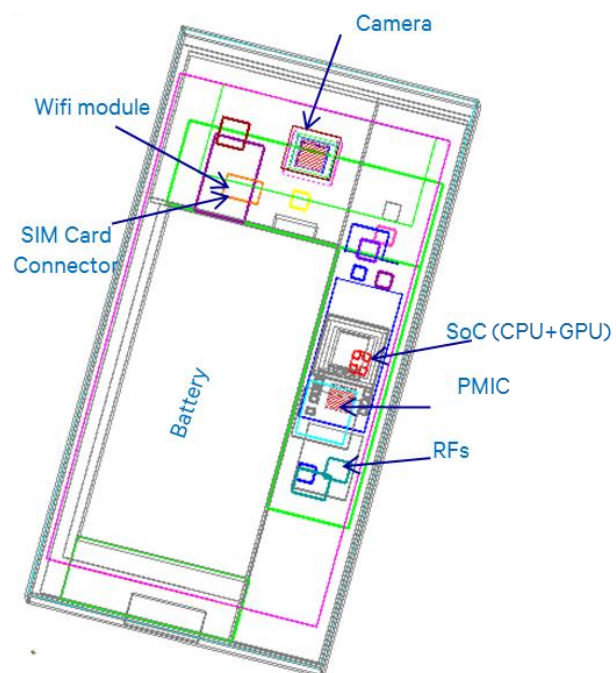
Thermal Implications of 3D ICs



Thermal Model Setup – Die, Package and Cooling Mechanism

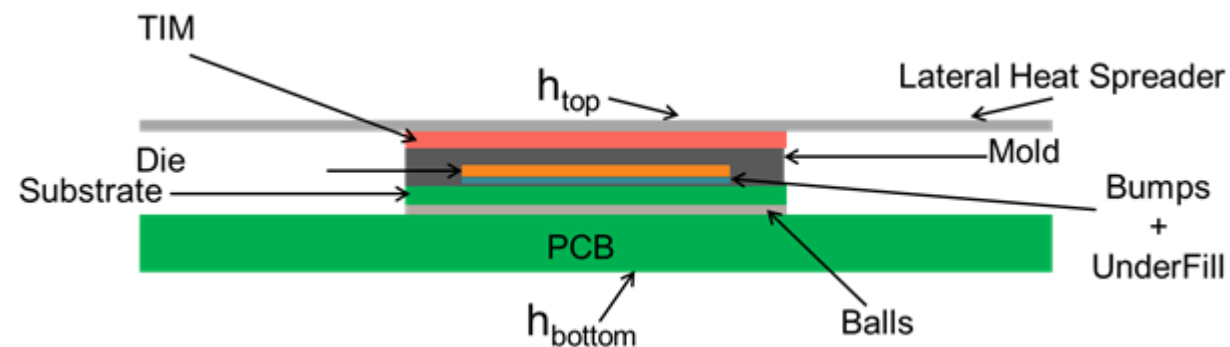
- Compact model derived from full system cellphone model
- SoC temperature matched with full system model

Typical Mobile Full System Thermal Model



Compact Model

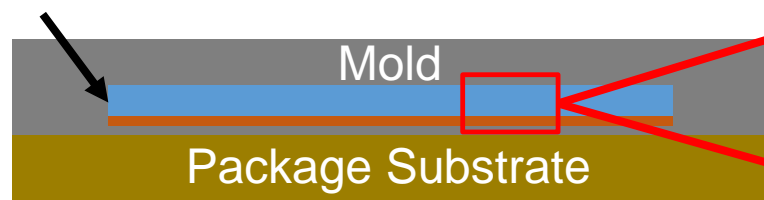
(SoC Package, board and top side heat spreader only)



Thermal Model Setup – F2B and F2F Stack up

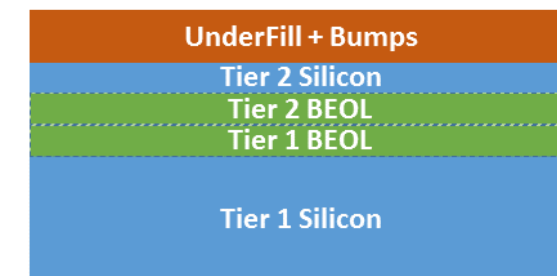
- 3D stack-up for Face-to-Face (F2F) and Face-to-Back (F2B)
 - Back-End-Of-Line (BEOL) modeled as one layer with effective thermal properties
 - Tier 2 Silicon with vertical connections modeled as one layer with effective thermal properties

Tier 1 silicon



(a)

(a) F2B stack-up

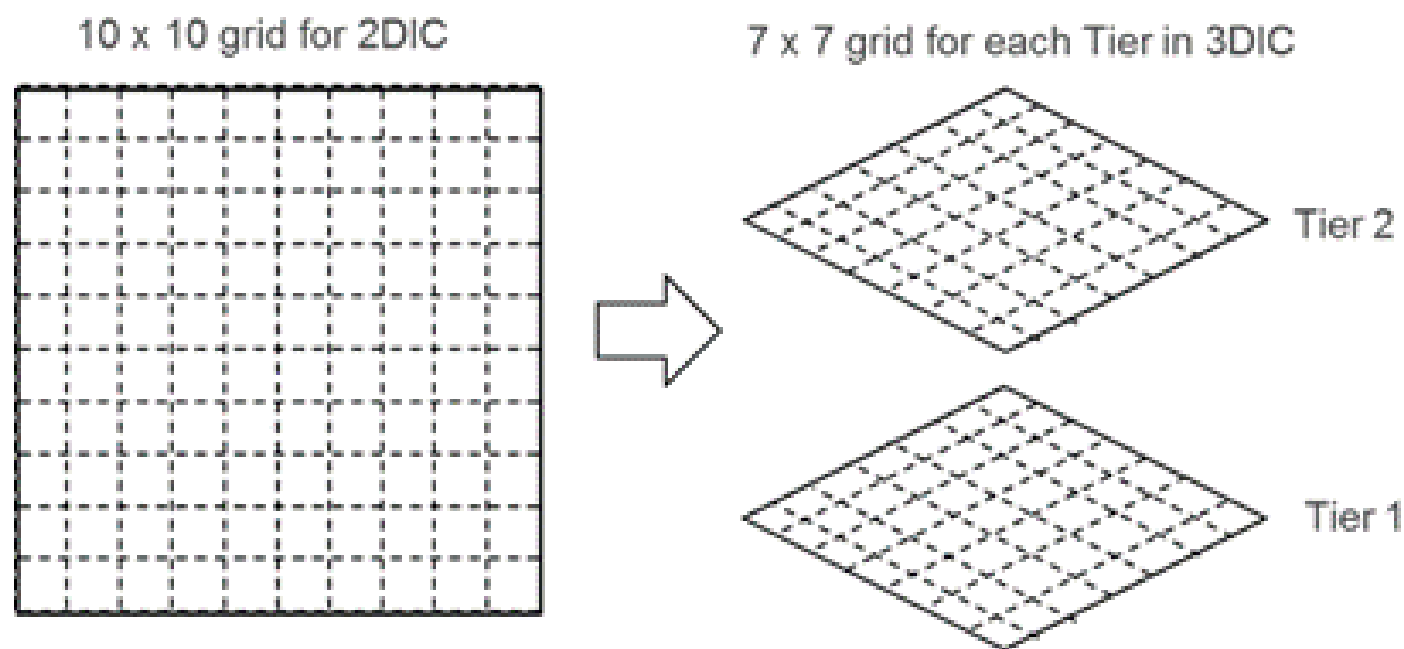


(b)

(b) F2F stack-up

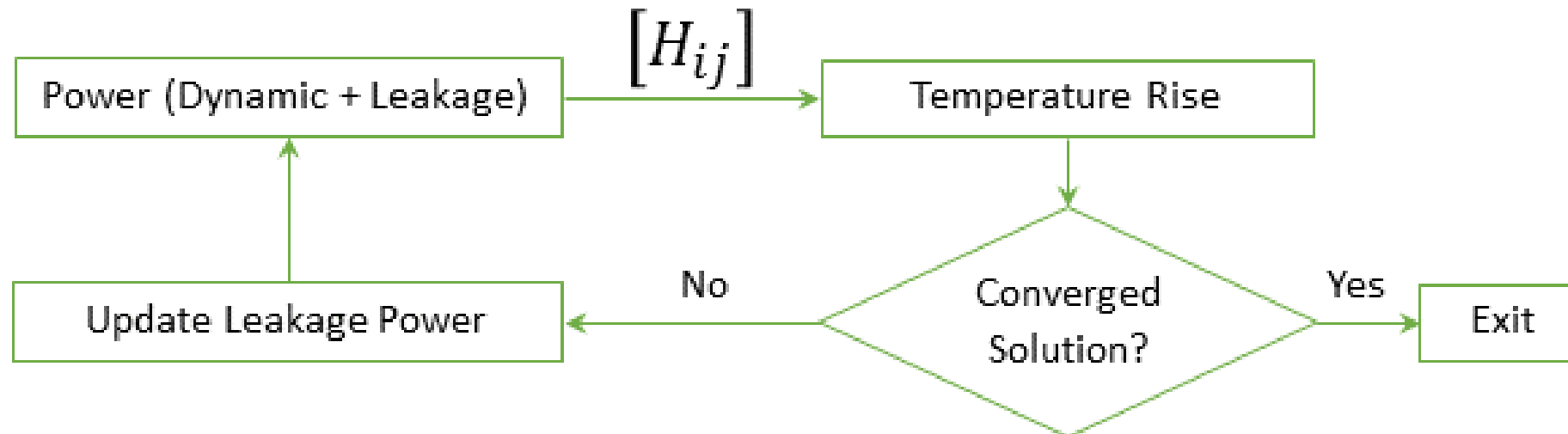
Model Generation – Power Mapping

- 2D and 3D silicon areas are similar ~ 50% area footprint shrink
- 1x1 mm² squares → 100 mm² 2D design



Model Generation – Simulation Methodology

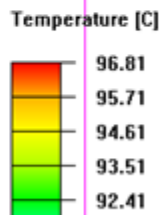
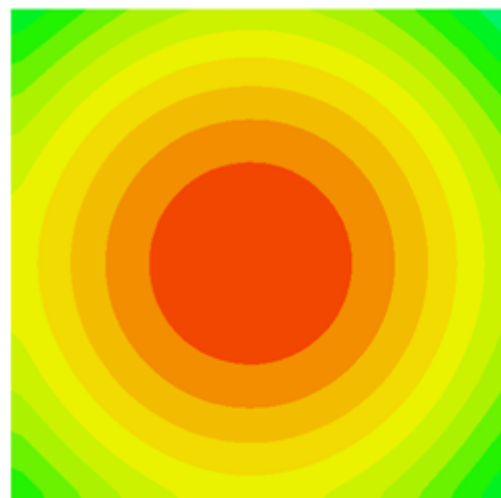
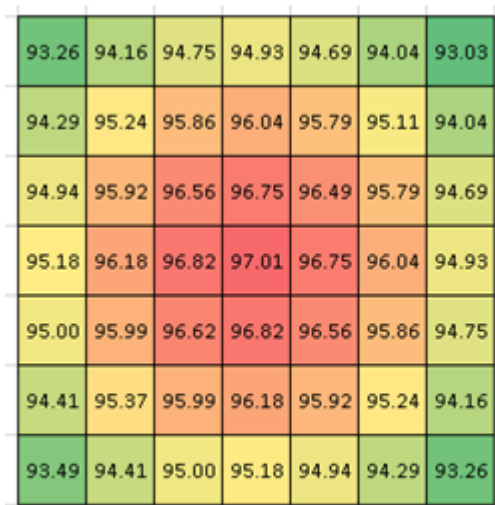
- Influence coefficient methodology
- $\Delta T = \sum H_{ij} \times P_i$
- Temperature-dependent leakage power loop



ICM Model Accuracy

- ICM based solver data compared with simulation using commercial thermal analysis tool, ICEPAK
 - Temperature delta (ICM- ICEPAK) = 0.2 °C
- Excellent match achieved between finite-volume analysis vs. ICM method

SoC Temperature distribution



(a) Our proposed model

(b) Commercial Solver

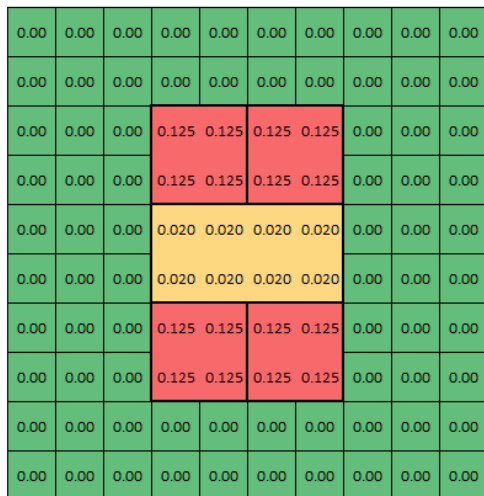
SoC Temperature Difference

| ICM Max Temp (°C) | Commercial Solver Max Temp (°C) | Temp Rise Diff (°C) | % Temp Rise Diff |
|-------------------|---------------------------------|---------------------|------------------|
| 97.0 | 96.8 | 0.2 | 0.3 |

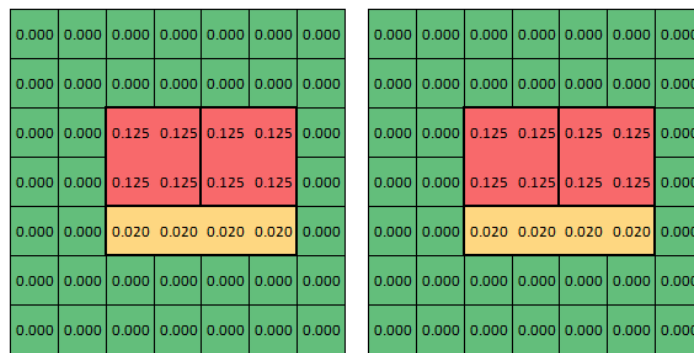
3D Thermal Characteristics

- Power input: power distribution for a typical quad-core CPU case
- Results: Temperature difference between tiers is small < 1° C
 - Distance between tiers is very small → small thermal resistance between tiers → good mutual heating
 - Power is low on each tier: $\Delta T = R \times P$

Dynamic Power Distribution



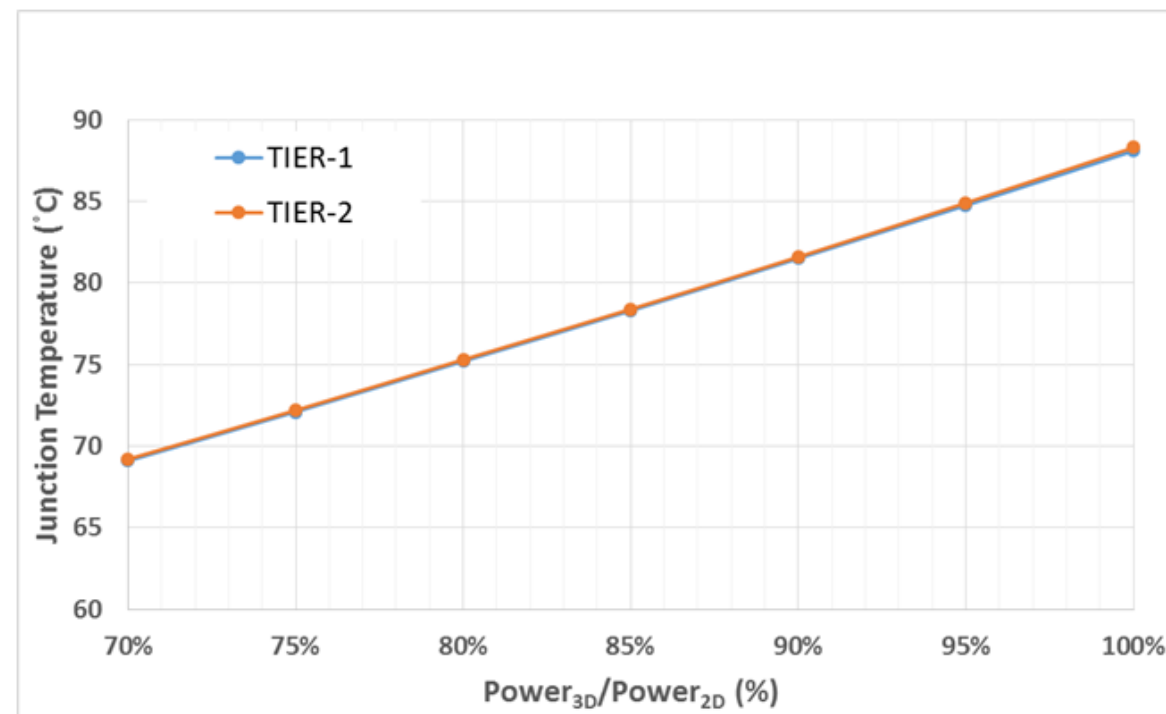
(a) 2D design



Tier 1

Tier 2

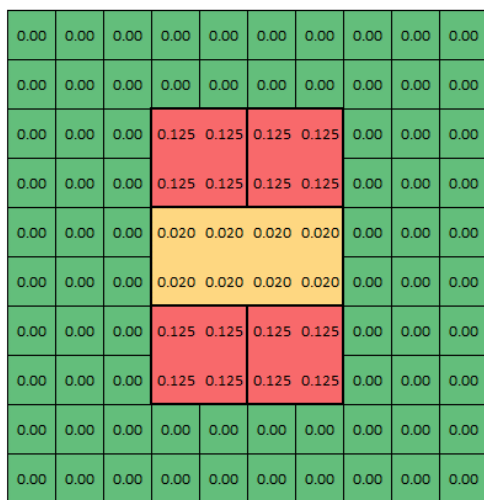
(b) Corresponding 3D design



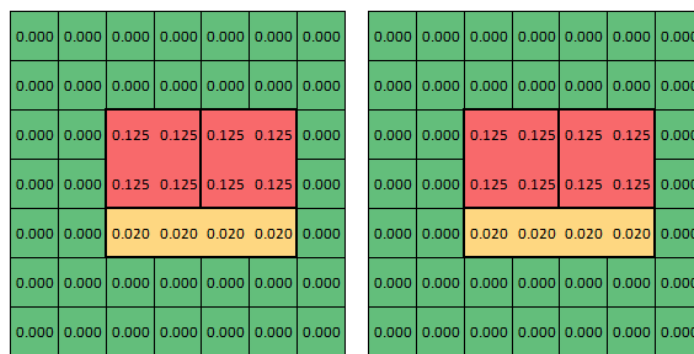
3D Thermal Characteristics – F2B vs. F2F Integration

- Power input: power distribution for a typical quad-core CPU case
- F2F integration is slightly hotter than F2B (~ 1° C)
 - In F2F, the active layers are closer to each other
 - In F2B there is a layer of thin silicon between the two tiers which slightly helps with temperature reduction

Dynamic Power Distribution



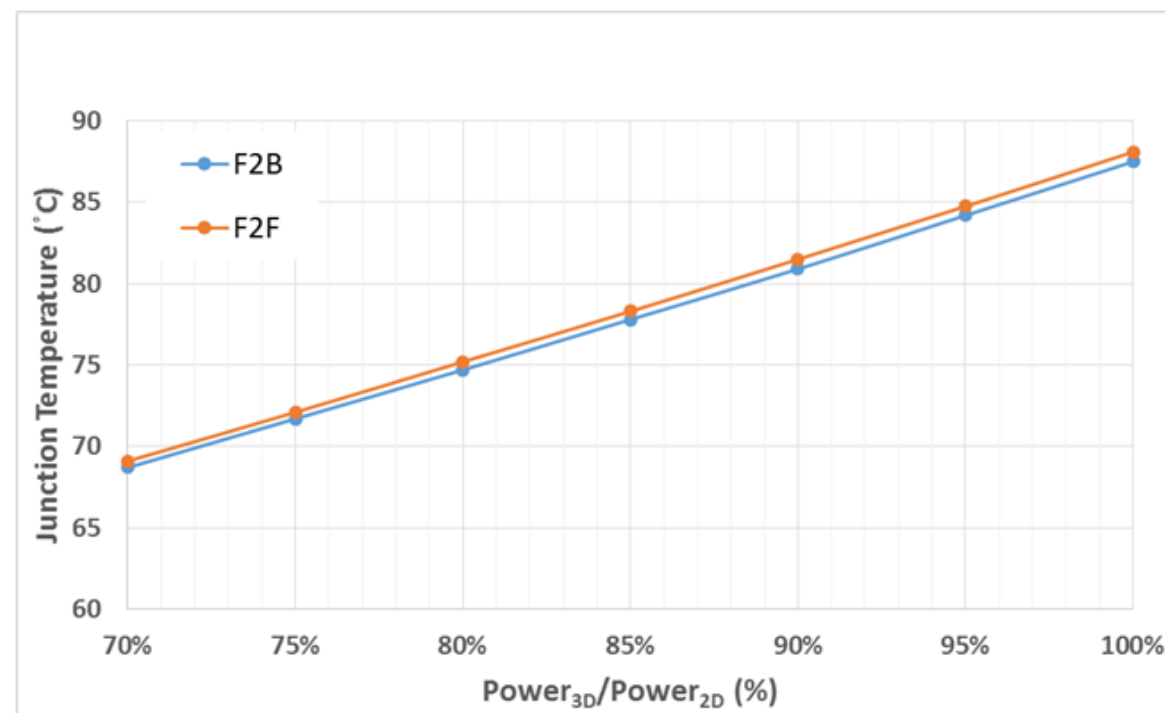
(a) 2D design



Tier 1

Tier 2

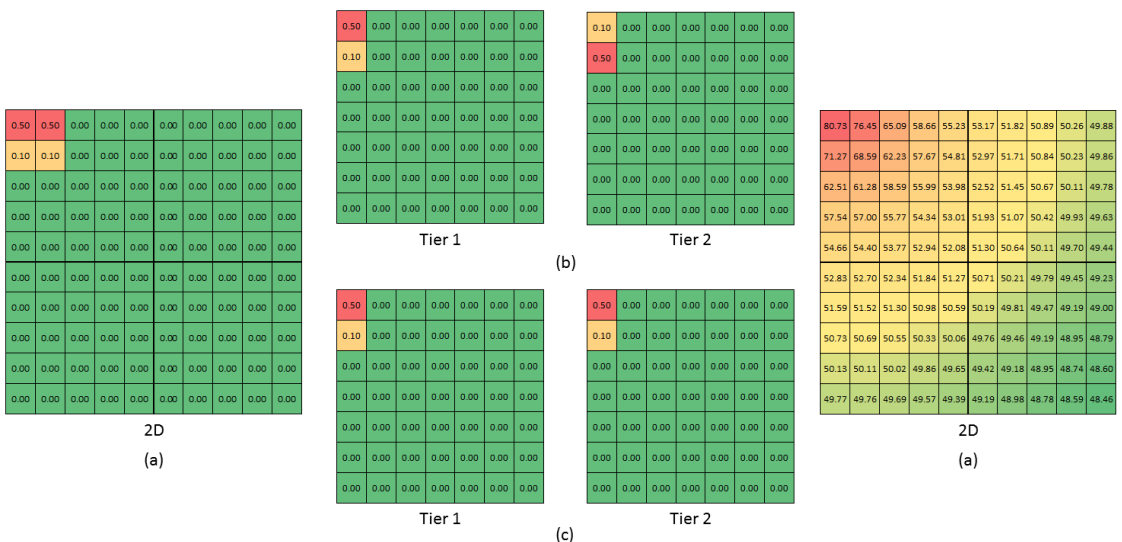
(b) Corresponding 3D design



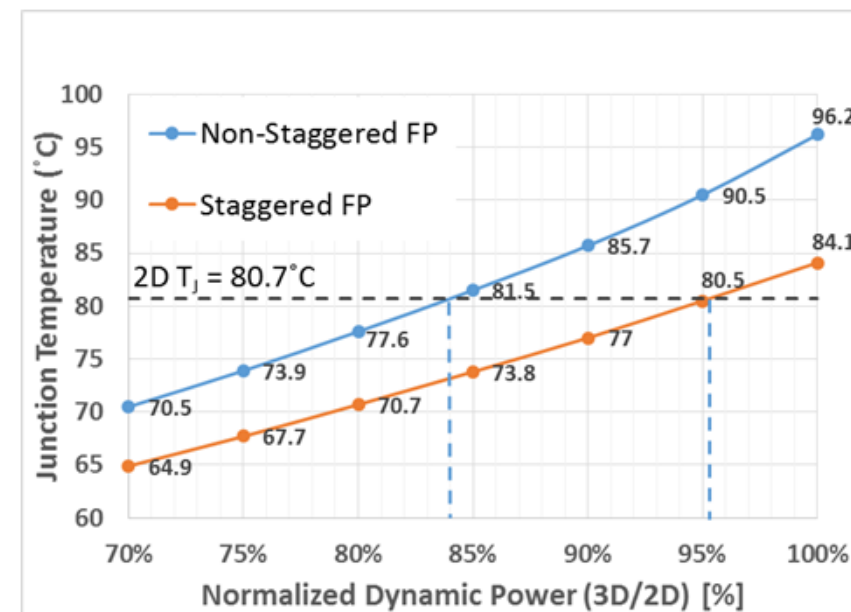
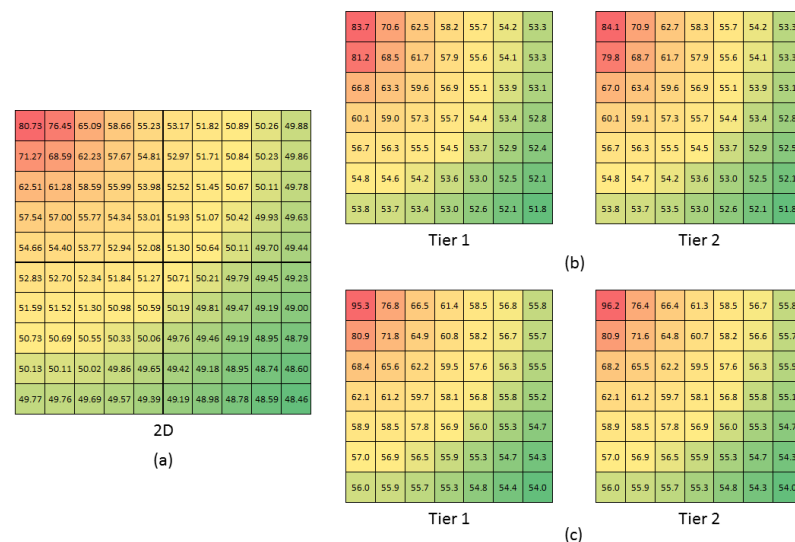
Temperature Rise in 3D vs. 2D: IP Block Partitioning Impact

- With the same power inputs, 3D temperature is higher than 2D
- 3D temperature is very sensitive to IP block partitioning
 - Non-staggered partitioning results in higher junction temperatures, requiring 16% power reduction in 3D to match 2D
 - With only 5% power reduction in staggered partitioning, 3D temperature matches with 2D

Dynamic Power Distribution (W)



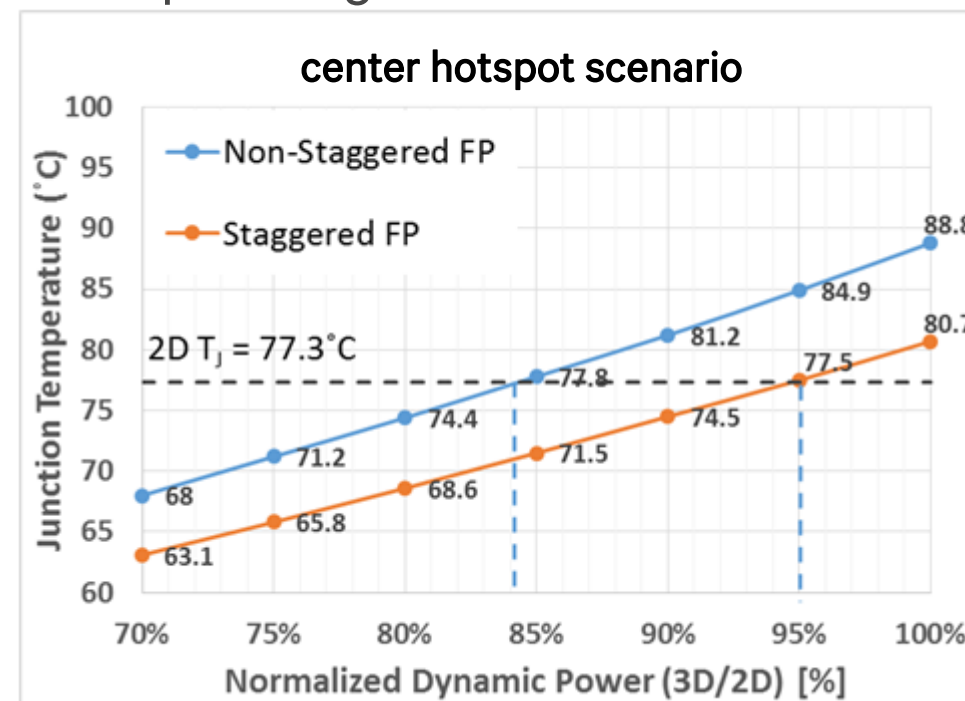
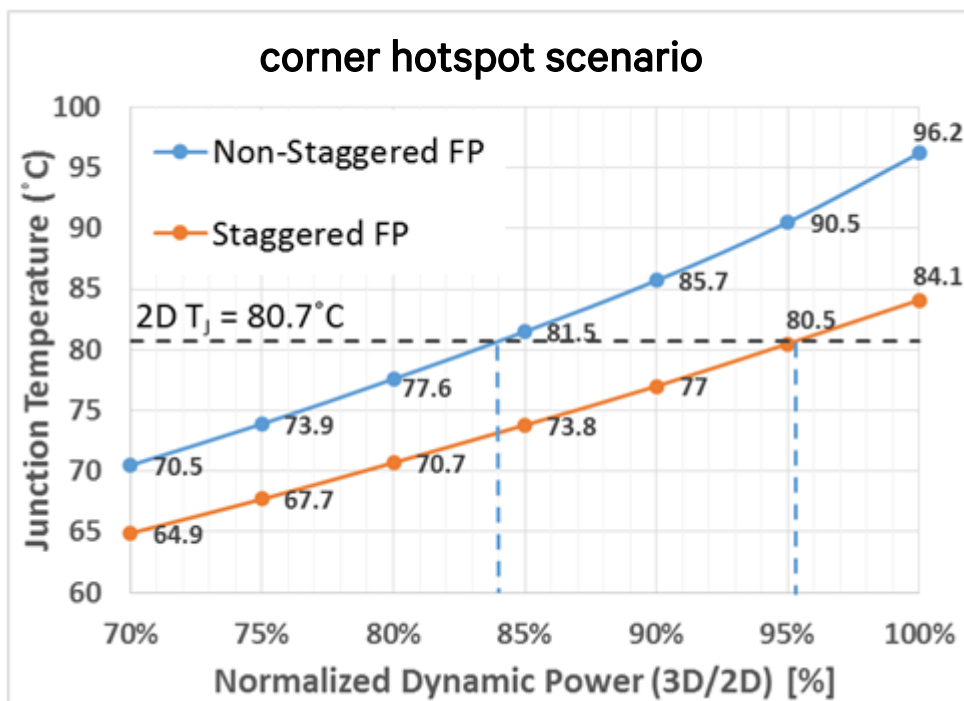
Temperature Distribution (°C)



(a) Baseline 2D, (b) Staggered and (c) Non-staggered designs

Temperature Rise in 3D vs. 2D: Floorplanning Impact

- 3D thermal risk is lower if the high power density is placed in the center of the die
 - Temperature rise is significantly lower for center IP block (96.2C vs. 88.8C)
- Power saving requirement is the same for both floorplans
 - ~5% for staggered partitioning
 - ~16% for non-staggered partitioning
- Power saving is more sensitive to partitioning than floorplanning

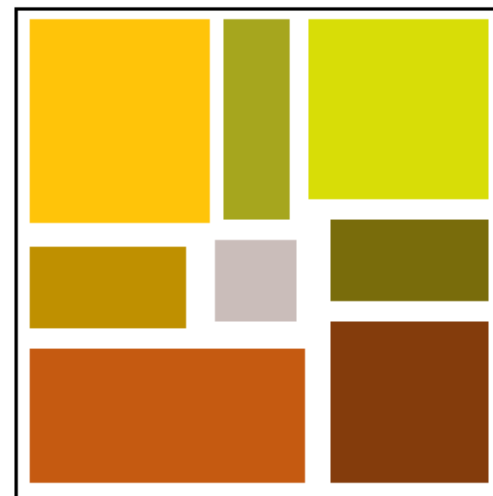


Power Saving Opportunities in 3D

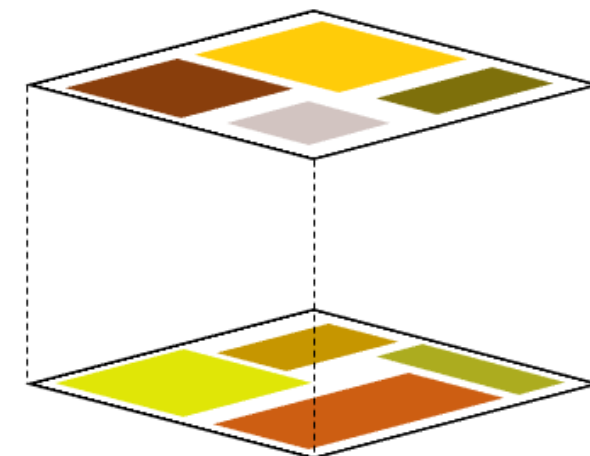
- Power savings are primarily coming from wirelength and buffer reductions
- $P_{total} = p_{internal} + p_{switching} + p_{leakage}$
- $p_{switching}^{3D} = (\alpha \cdot c_{pin} + \beta \cdot c_{wire}) \cdot p_{switching}^{2D}$
- Internal and leakage components are proportional to total cell area

Floorplanning and Partitioning Options in 3D

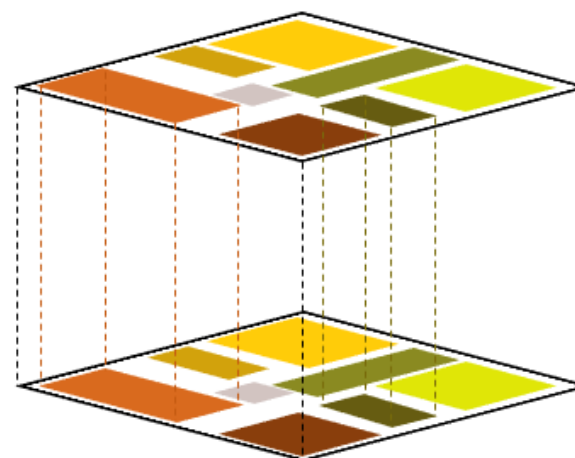
- (a) 2D block partitioning with 2D floorplanning
- (b) 2D block partitioning with 3D floorplanning
- (c) 3D block partitioning with 2D floorplanning
- (d) Combination of 2D and 3D block partitioning with 3D floorplanning



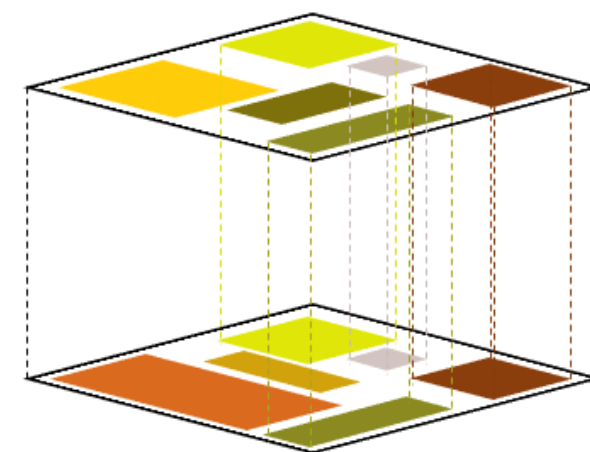
(a)



(b)

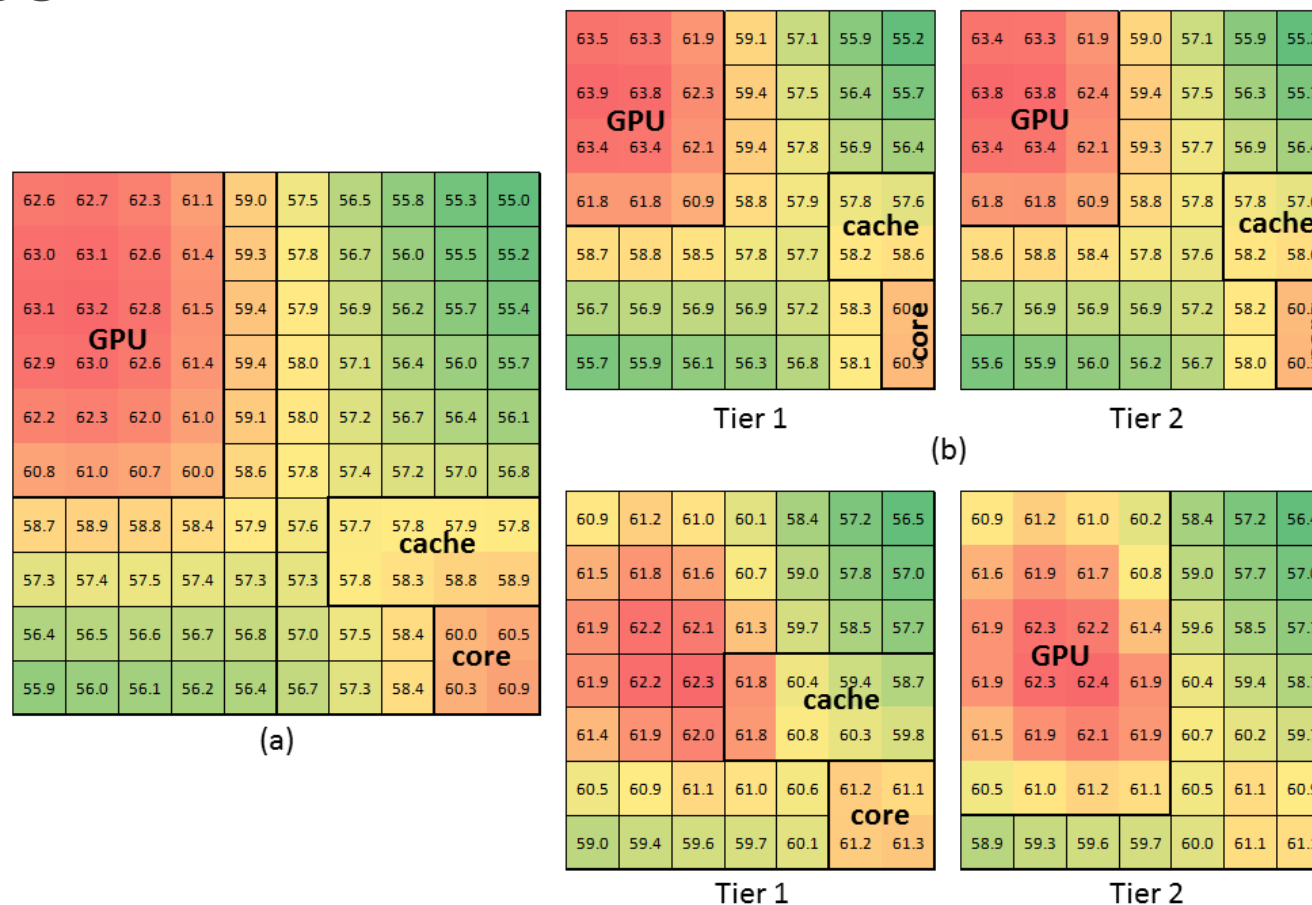


(c)



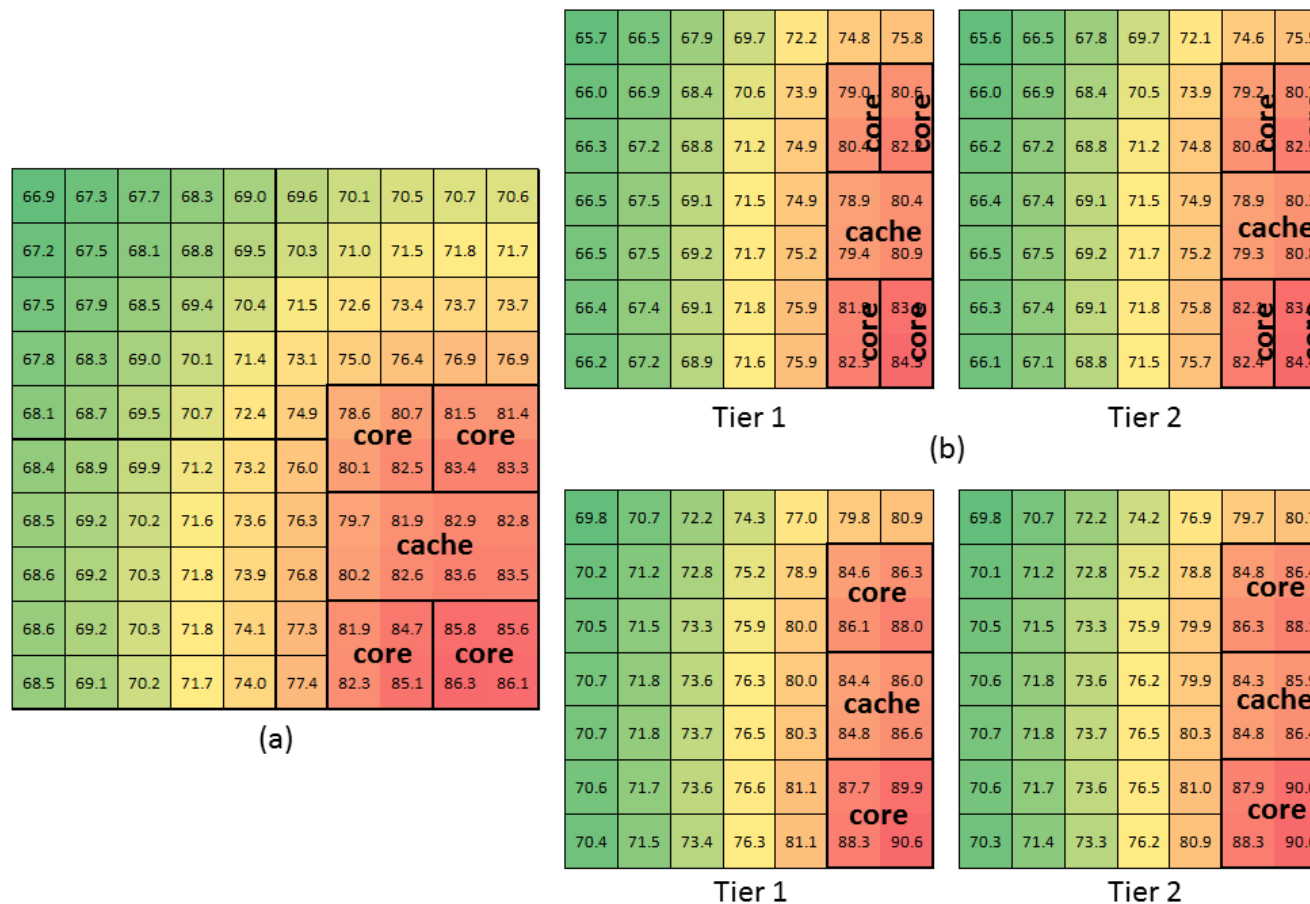
(d)

3D Floorplanning and Partitioning Case Study: GPU Power Intensive Case



Thermal maps of mobile MPSoC GPU intensive use-case for (a) 2D, (b) All 3D and (c) All 2D configurations

3D Floorplanning and Partitioning Case Study: CPU Power Intensive Case



Thermal maps of mobile MPSoC CPU intensive use-case for (a) 2D, (b) All 3D, and (c) All 2D configurations

Summary of 3D Floorplanning and Partitioning Case Study

- 3D temperatures with appropriate partitioning / floorplanning are comparable (or even) better than 2D

| Scenario | Configuration | Partitioning | TIER-1 Tj [C] | TIER-2 Tj [C] | Leakage TIER-1 [W] | Leakage TIER-2 [W] | Total power (W) |
|---------------|---------------|--------------|---------------|---------------|--------------------|--------------------|-----------------|
| GPU Intensive | 2D | | 63.2 | | 0.49 | | 2.07 |
| | 3D (Baseline) | All 2D | 64.9 | 65 | 0.21 | 0.32 | 2.11 |
| | 3D | All 2D | 62.3 | 62.4 | 0.19 | 0.28 | 1.971 |
| | 3D (Baseline) | All 3D | 68.9 | 68.9 | 0.28 | 0.28 | 2.14 |
| | 3D | All 3D | 63.9 | 63.8 | 0.24 | 0.24 | 1.901 |
| | 3D (Baseline) | Hybrid | 68.9 | 68.9 | 0.38 | 0.17 | 2.13 |
| | 3D | Hybrid | 64.3 | 64.3 | 0.33 | 0.15 | 1.921 |
| CPU Intensive | 2D | N/A | 86.3 | | 0.85 | | 3.01 |
| | 3D (Baseline) | All 2D | 98.3 | 98.3 | 0.57 | 0.57 | 3.3 |
| | 3D | All 2D | 90.6 | 90.6 | 0.45 | 0.45 | 2.952 |
| | 3D (Baseline) | All 3D | 98.3 | 98.3 | 0.57 | 0.57 | 3.3 |
| | 3D | All 3D | 84.5 | 84.4 | 0.39 | 0.39 | 2.68 |

Conclusions

- **Practical and cost efficient 3DVLSI technologies are emerging**
- **A new generation of implementation tools are required to take full advantage of 3DVLSI technology**
 - Floorplanner
 - Place & Route
 - Extraction
 - Timing
 - CTS
- **New design methodologies are required**
 - New Architectures
 - New foundation IP structures

Qualcomm Research

Thank you

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